LABORATOIRE DE L'ACCÉLÉRATEUR LINÉAIRE
Centre scientifique d'Orsay
Bât 200 - BP 34
F-91898 ORSAY cedex
www.lal.in2p3.fr - UMR 8607

Le 16/06/2017

Introduction to High Vacuum in Accelerators

Mercier Bruno LAL

Introduction to High Vacuum in accelerators.

Part1: vacuum basis

1-1 Kinetic behavior of gas molecules

1-2 Mean free path / residence time

1-3 outgassing/desorption

Part2: vacuum in accelerators

2-1 interaction residual gas - beam

2-1-a Coulomb scattering

2-1-b Bremsstrahlung

2-1-C Ionization energy loss

2-1-d ion accumulation

2-2 Interaction particules surface

2-2-a Synchrotron radiation an Photon stimulated desorption

2-2-b Ion stimulated Desorption

2-2-c Electron stimulated Desorption an electron-cloud

Part3: Technologie evolution

3-1 Pressure distribution in accelerators

3-2 Distributed pumping

3-2-a getter pump

3-2-b NEG coating

What does vacuum mean?

Vacuum: an absence of matter ?

- Space where the molecules are strongly rarefied compared to atmospheric pressure

10^{-9} mbar ~ 25 millions/cm^3 at 20°C

Pollution source, background noise, parasitic interactions ....

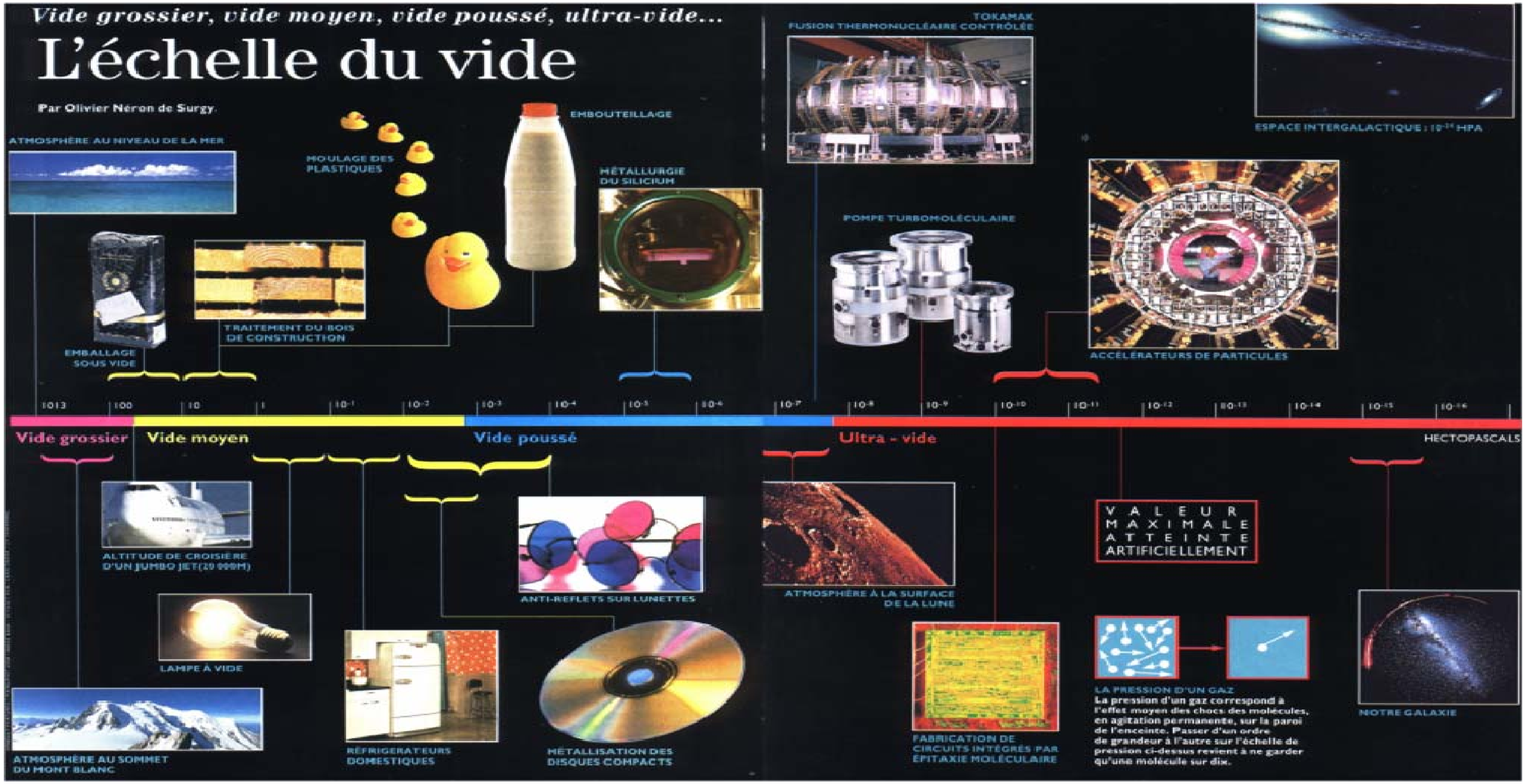
- quantum vacuum:

State minimum energy, vacuum fluctuation, ...

a vacuum: full of matter !!

The scale

Pressure 100 Pa(N/m^2) = 1 mbar = 0,75 Torr

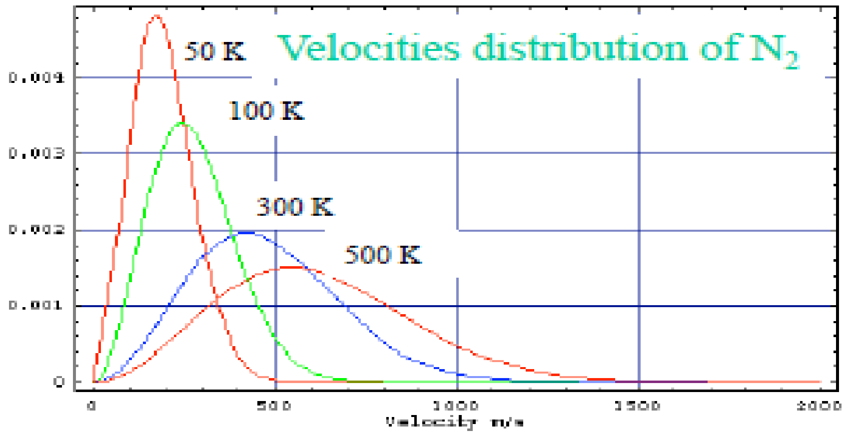


Maxwell-Boltzmann velocity distribution

$$\overline{V} = V_m = \sqrt{\frac{8R.T}{\pi.M}} \qquad V_{rms} = c = \sqrt{\frac{3R.T}{M}}$$

At 20°C — Ar ~ 394 m/s — N_2 ~ 471 m/s, He ~ 1246 m/s

Dependent upon composition of gas and temperature



residence time on the surface

Frenkel formul

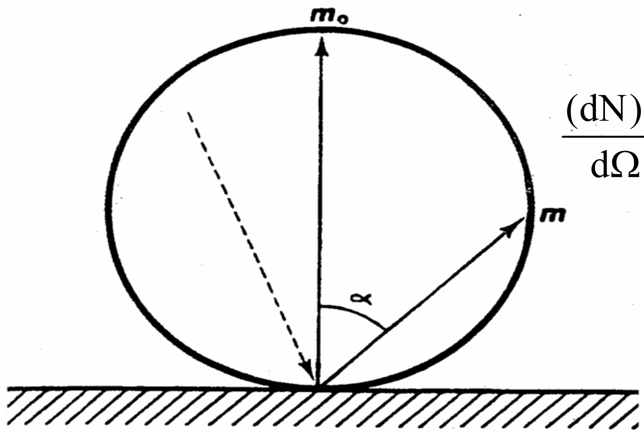
τ_0 ~ 10^{-13} s

$$\tau = \tau_0 \cdot e^{\frac{E}{RT}}$$

E desorption energy

20 < E < 25 kcal/mol → 30 s < τ < 5 days at 20 °C

Increase pumping time



$$\frac{(dN)_\theta}{d\Omega} = \frac{N}{\pi}\cos(\theta)$$

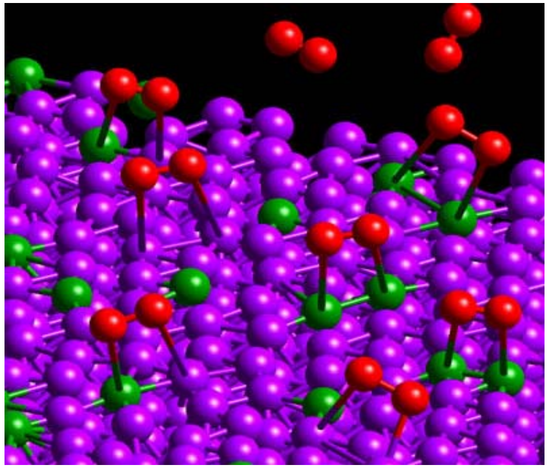
Emission under cosine law

Monolayer formation time

And considering the molecule as spherical, for perfect atomic arrangement:

$$\tau = \frac{4}{d^2 . n . v_m}$$

(very approximate)



Order of magnitude one monolayer ~ 10^{15} molécules/cm^2

τ ~ 40 min at $P=10^{-9}$ mbar (N_2)
τ ~ 3 sec at $P=10^{-6}$ mbar (N_2)

The concept of monolayer can appreciate the cleanliness of the surface

Mean Free Path

It is the path length that a molecules traverse between two succesives impacts with other molecules.

$$l_m = \frac{1}{\sqrt{2}\pi . d^2 . n}$$

l_m ~ 64 km at $P=10^{-9}$ mbar (N_2)
l_m ~ 6.5 m at $P=10^{-6}$ mbar (N_2)

Vacuum basis :

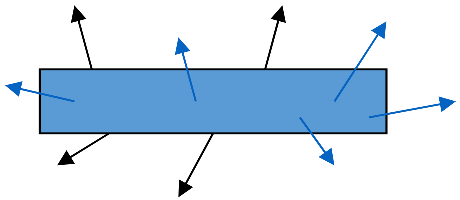
summary Tables

Pour N_2 at 20°C

Pressure (hPa)	Strength per unit area	density molecular (molecule/cm^3)	Mean free path	Impingement rate (per cm^2 and per sec)	Monolayer formation time
1013	1 kg/cm^2	2,50x10^{19}	0,1 µm	2,9x10^{23}	3,4x10^{-9} s
1	1 g/cm^2	2,47x10^{16}	0,1 mm	2,9x10^{20}	3,4x10^{-6} s
10^{-3}	1 mg/cm^2	2,47x10^{13}	10 cm	2,9x10^{17}	3,4x10^{-3} s
10^{-6}	1 µg/cm^2	2,47x10^{1}	100 m	2,9x10^{14}	3,4 s
10^{-9}	10 µg/m^2	2,47x10^{7}	100 km	2,9x10^{11}	1 heure
10^{-12}	0,01 µg/m^2	2,47x10^{4}	10^{5} km	2,9x10^{8}	40 jours
10^{-16}	1 µg/km^2	2,47	10^{9} km	2,9x10^{4}	1000 ans
10^{-23}	10^{-7}µg/km^2	2,47x10^{-7}	10^{16} km	2,9x10^{-3}	10^{10} ans

outgassing

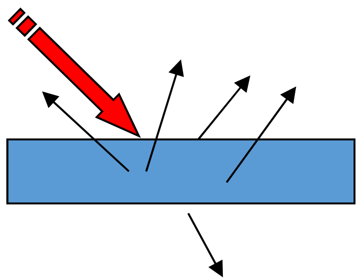
Outgassing is the spontaneous evolution of gas from solid or liquid.



desorption /degazing

Desorption is the release of adsorbed chemical species from the surface of a solid or liquid.

Particules (ions, photons, electrons,….)



Desorption: gas flow

At the thermodynamic equilibrium

Gas flow

$$Q = P\frac{dV}{dt} = PS = \frac{dN}{dt}KT$$

S effectif pumping speed
N molecule number

$Pa.m^3/s$ (=10 mbar.l/s)

The outgassing rate τ : a gas flow per unit of surface

$$\tau = Q / A$$

A desorption area

$Pa.m^3.s^{-1}.m^{-2} = Pa.m.s^{-1}$ ($=10^{-3}$ $mbar.l.s^{-1}.cm^{-2}$)

Importance of the gas flow

At the thermodynamic equilibrium, the pressure in the system is expressed by:

$$P = \frac{\sum Q}{S} + P_0$$

P_0 limit pressure of pumping system

S effectif pumping speed

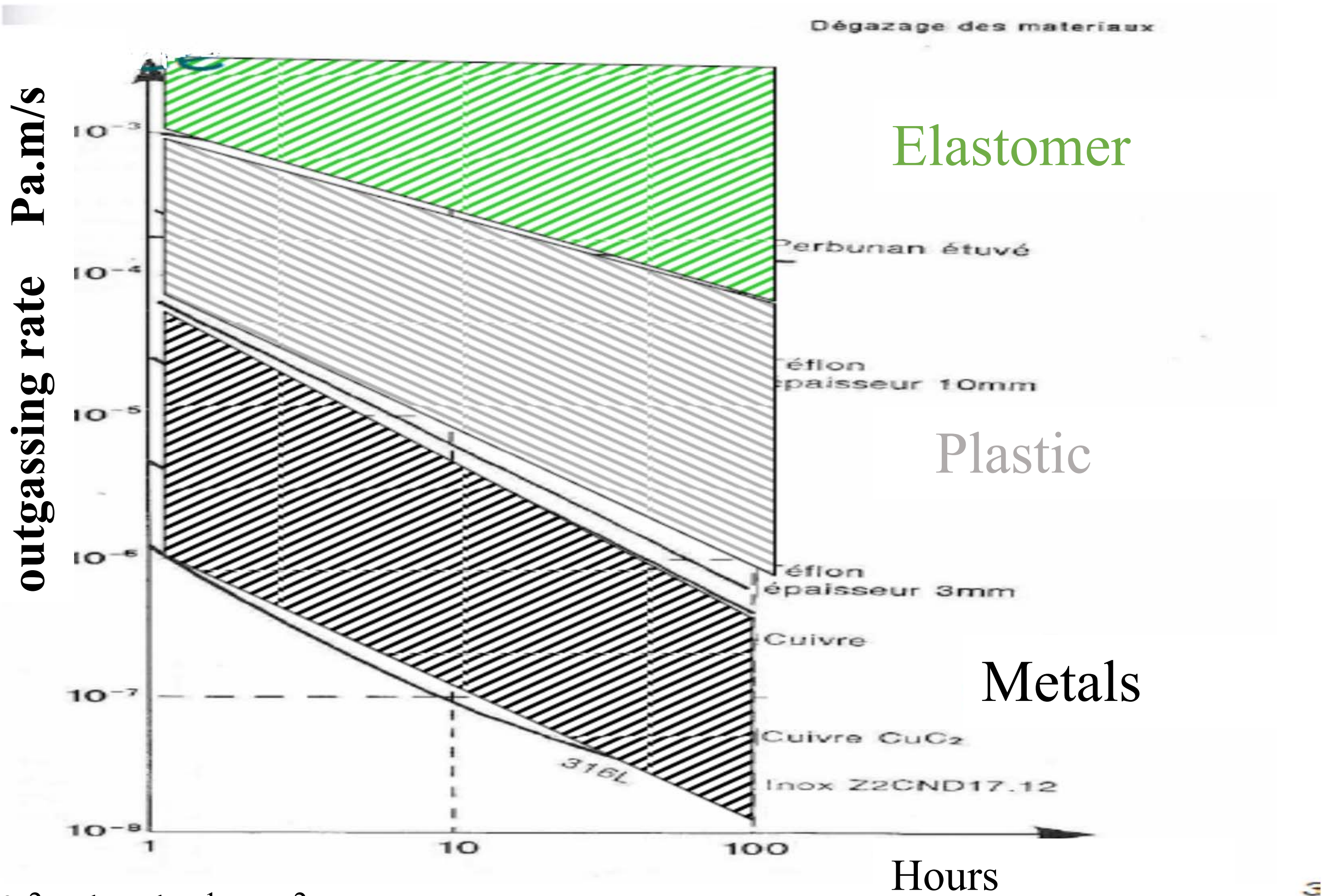
Decrease of the work presssure P

- **Increase the pumping speed** — Approximately 2 to 3 orders of magnitude with a high cost and limited effectiveness conductances
- **Decrease the flow** — About 10 orders of magnitude depending on the choice of materials and treatments

Attention to minority surfaces

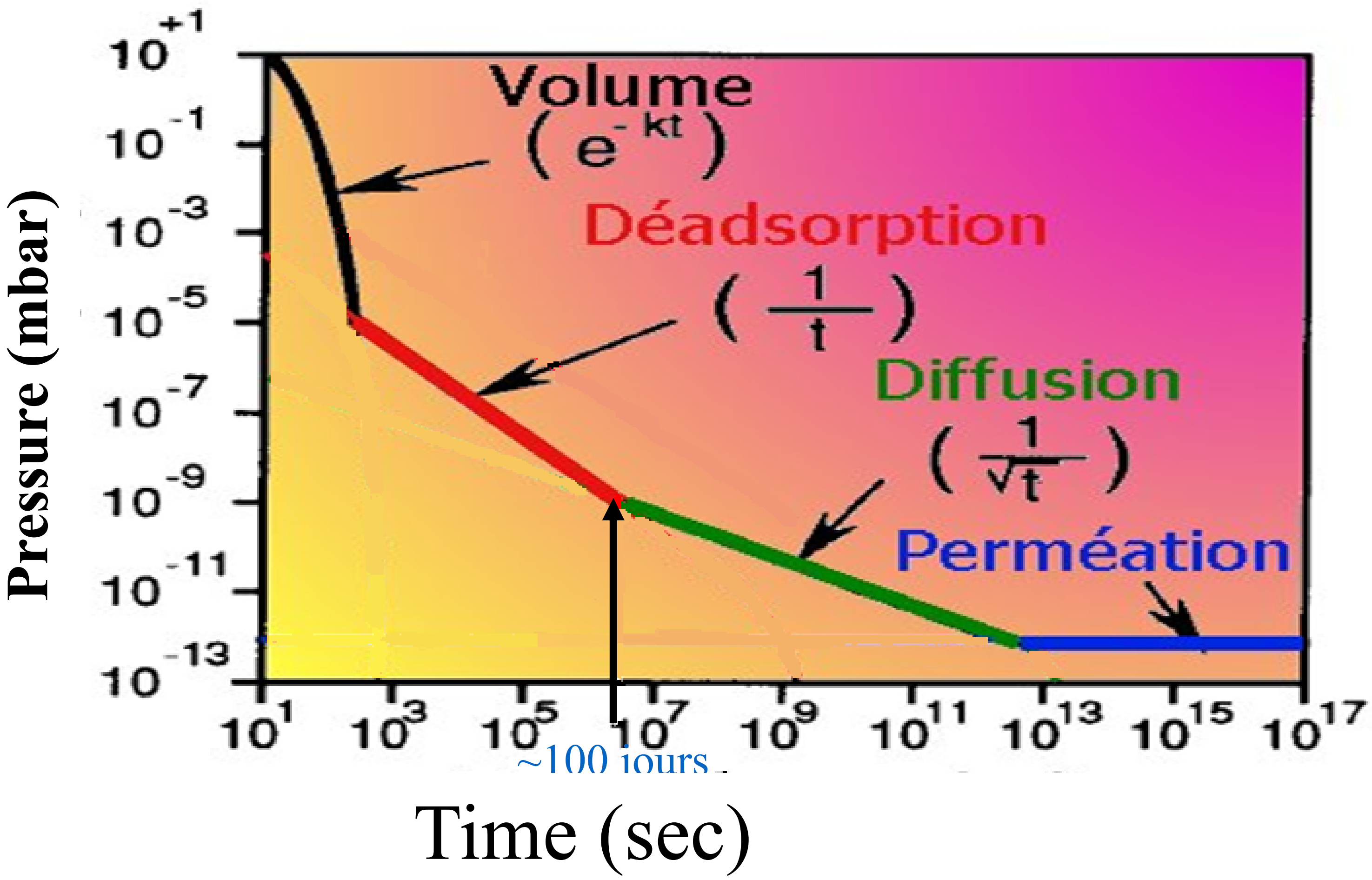
First of all decrease the degassing rates

Time dependance of the outgassing flow rate for différent materials

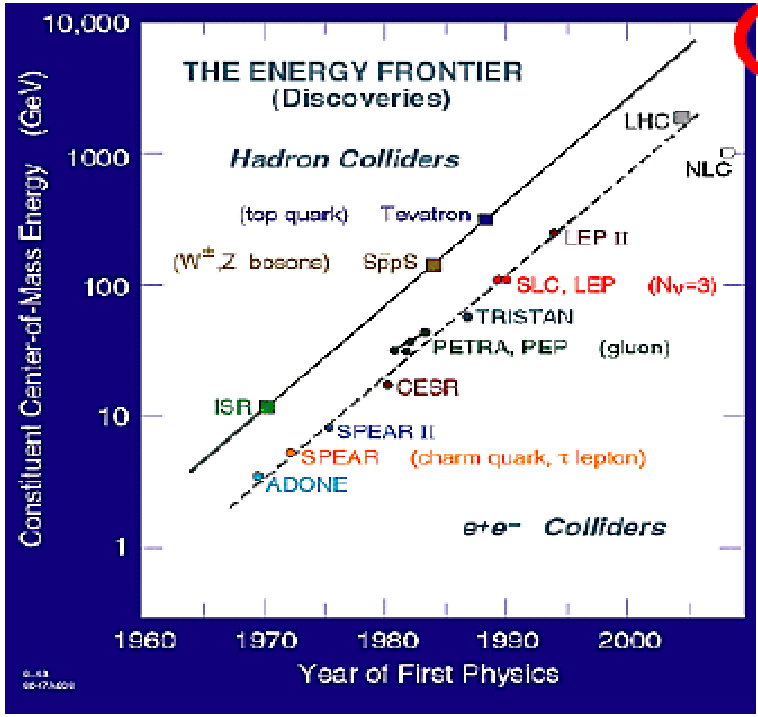


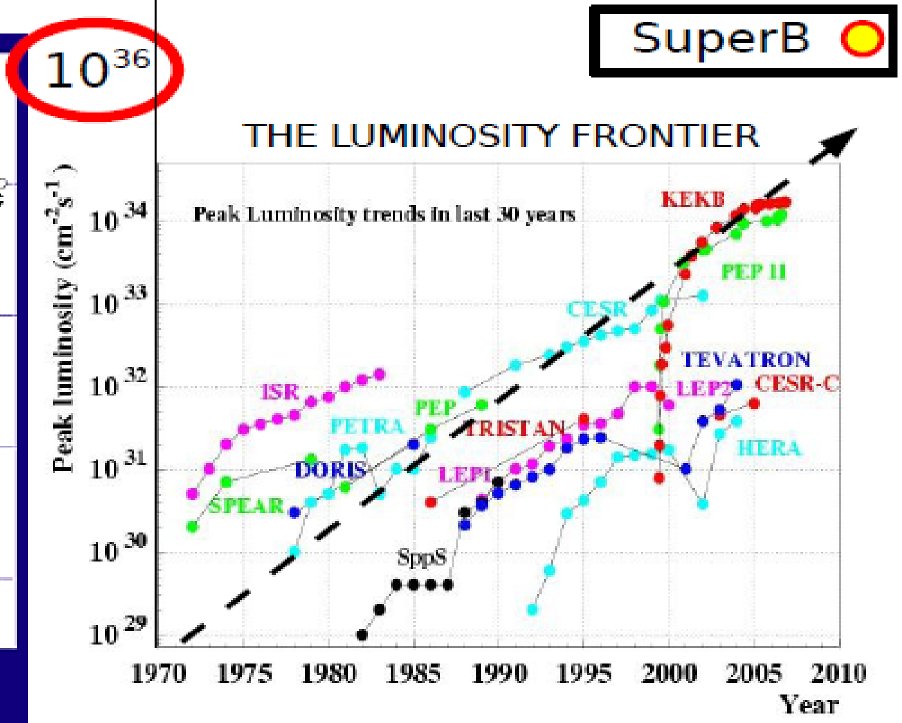
1 Pa.m/s = 10^{-2} mbar.l.s^{-1}.cm^{-2}

The pressure vs. Time behavior of a typical vacuum system (metal chamber)



Vacuum in accelerators :





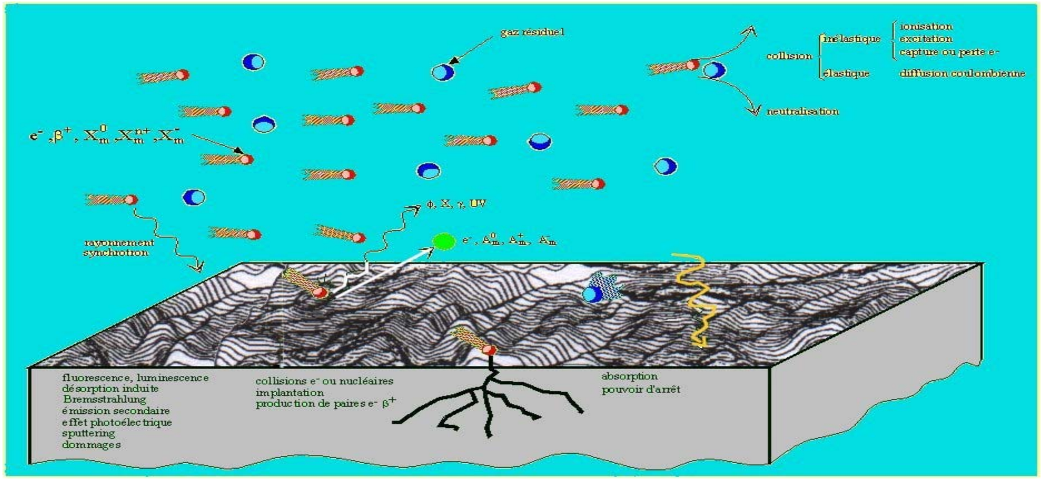
$$\mathcal{L} \sim f_{\rm coll} \frac{N^+ N^-}{4\pi \sigma_x \sigma_y} = 10^{36}\ \mathrm{cm}^{-2}\ \mathrm{s}^{-1}$$

High luminosity

small beam, high intensity and high frequency

Level and quality of the residual gas (dynamic pressure ~ 10^{-9} mbar)

Vacuum in accelerators :



Beam & Vacuum & Surface: a difficult coexistence!

Interaction: Beam - résidual gas

- Changing the shape and the beam energy
- Secondary particule emission (ion,e-, photons)
- Loss of beam particules

Interaction: Particules (secondary, primary) - surface

- Desorption by electron, photon, ion impact
- Secondary emission

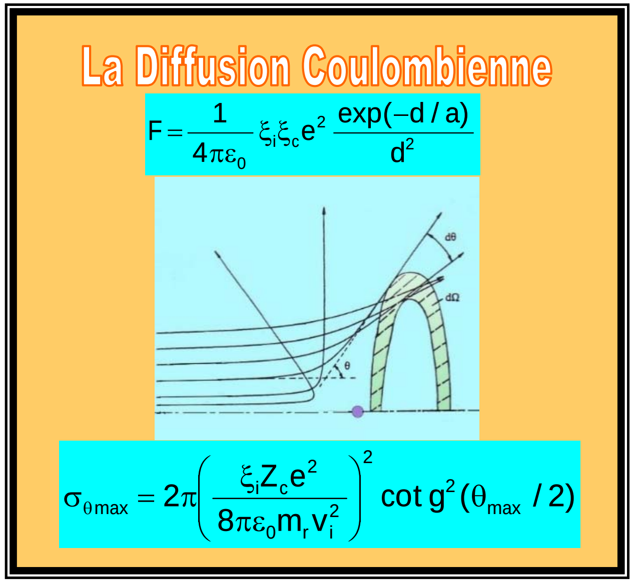
Interaction: Beam- residual gas

INTERACTION

- Elastic
  - **Single Coulomb scattering**
- Inelastic
  - **Bremsstrahlung**
  - **Ionization energy loss**
  - Electron capture
  - Electron loss
  - Nuclear reactions

Interaction: Beam- residual gas

Elastic interaction — Single Coulomb scattering



$$\frac{d\varepsilon}{dt} \propto Z^2 \cdot P$$

Emittance is proportional to residual gas pressure and depends sqare residual gas atomic number

Nuclear scattering LHC

Life time limit ~100h P~10-8 mbar H_2 equivalent

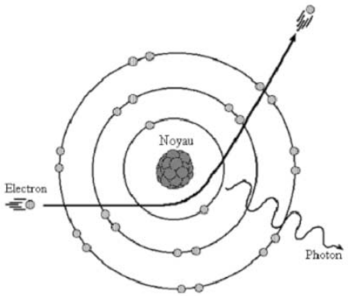
80 mW/m heat load in the cold mass

Interaction: Beam- residual gas

→ Inelastic interaction
- **Bremsstrahlung**
- Ionization energy loss
- Electron capture
- Electron loss
- Nuclear reactions

Bremsstrahlung

Material	Z	A	Radiation length X_0 [g/cm²] () is for gas	[cm]	Density [g/cm³] () is for gas [g/ℓ]
H_2	1	1.01	61.28	865	0.0708(0.090)
D_2	1	2.01	122.6	757	0.162(0.177)
He	2	4.00	94.32	755	0.125(0.178)
Li	3	6.94	82.76	155	0.534
Be	4	9.01	65.19	35.3	1.848



$$\frac{dE}{E} = -\frac{dx}{\chi_0}$$

Valid for light particules (e+,e-)

$$\chi_{0[g/cm^2]} = \frac{714.6A_c}{Z_c(Z_c+1)Ln(287/\sqrt{Z_c})}$$

Loss beam enregy

the radiation interacts with the surface → Desorption

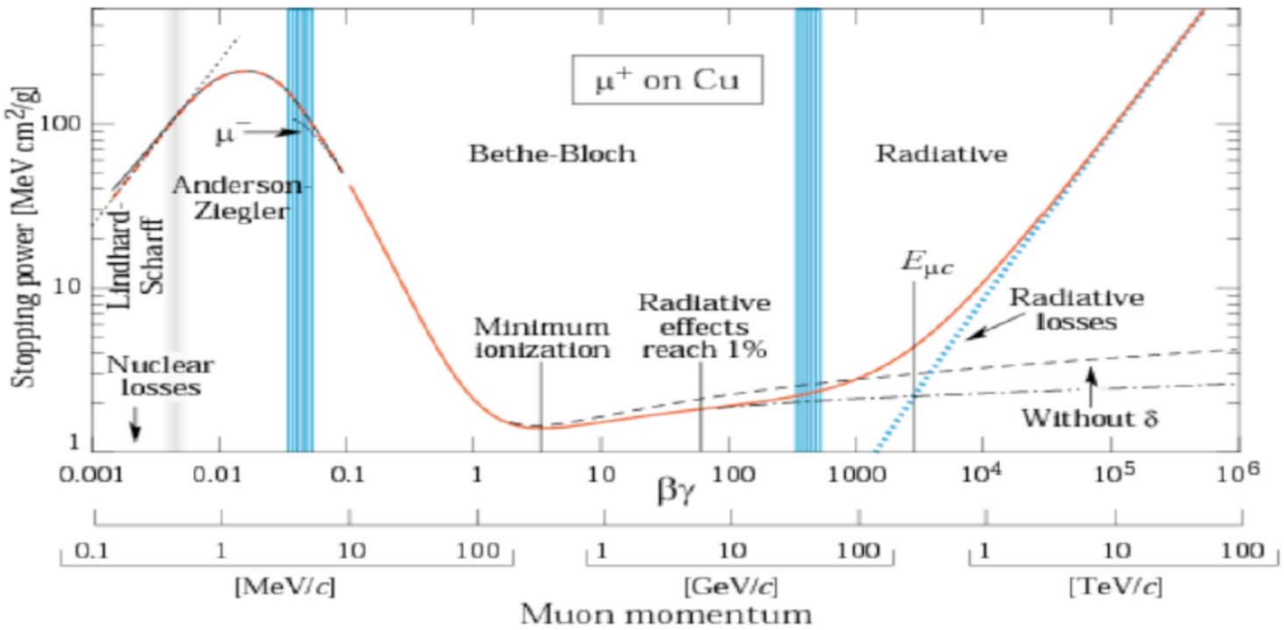
A very strong dependence on the target atomic number is observed, which means that even a small amount of a heavy gas may have a higher influence on the lifetime than the usually dominating hydrogen content.

about 4.10^6 times lower for proton

Interaction: Beam – residual gas

Inelastic interaction
- Bremsstrahlung
- **Ionization energy loss**
- Electron capture
- Electron loss
- Nuclear reactions

Ionization energy loss



Loss beam energy

Secondary particule emission: **electrons, ions** → Interaction on the surface and desorption

Ion accumulation

negative charge beam

An important phenomenon for negative charges beam, for high current and for short bunch spacing

Pressure due to the ion containment

mechanism:

ionisation of residual gas by beam

↓

Electric field (e- beam) focuces ions in chamber center

↓

Defocusing of ions between two bunch

↓

Oscillations and ions trapping and accumulation

consequence:

The pressure (seen by beam) increases

↓

Influence on beam dynamics

Ion accumulation

Ions stability criterion :

[1] Neutralisation of accelerator beams by ionisation of the residual gas Y. Baconnier, A. Poncet and P.F. Tavares CERN

Calculation of critical mass [1] :

All ions of mass greater than the critical mass will be accumulated.

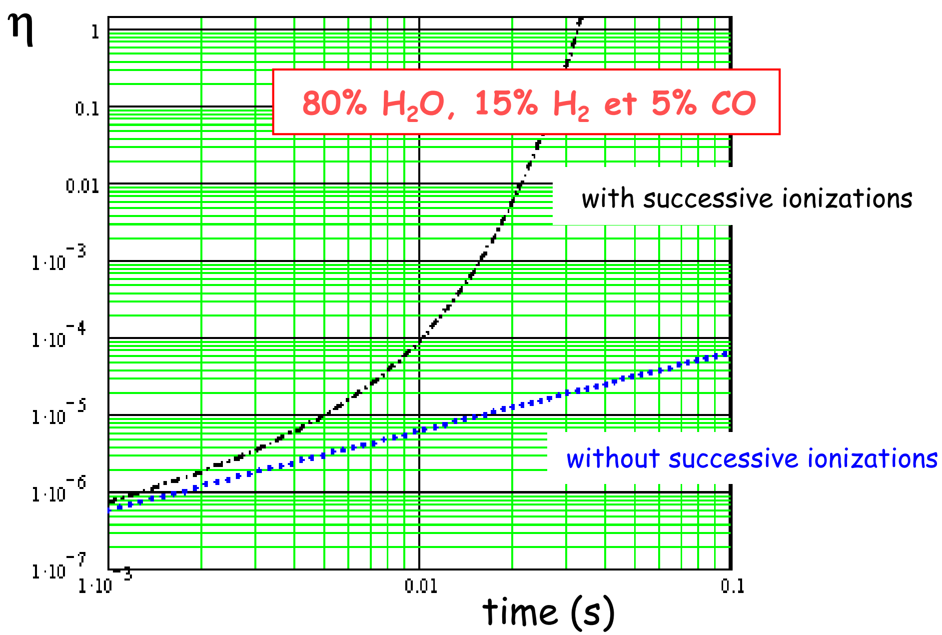
$$A_c = \frac{N_e}{N_b^2} \cdot r_p \cdot \frac{2 \cdot \pi \cdot R}{\beta \cdot b^2 \cdot (1 + a/b)}$$

avec Ne e- number, N_b bunch number, r_p proton radius, 2.π.R ring circumference, β ratio of *v* to the speed of light *c*, a and b beam size .

Neutralizing Factor

$$\eta = \frac{\text{number of positive charge (ions)}}{\text{Number of negative charge (beam electron)}}$$

Neutralizing factor Versus time



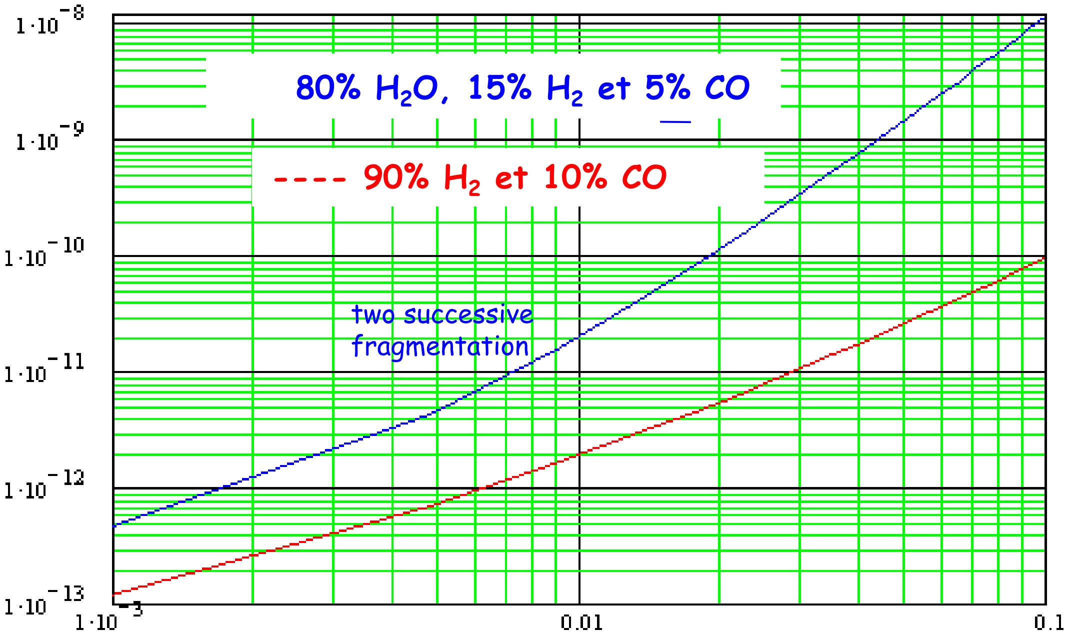
Ion accumulation

Ionic pressure seen by beam

Increased pressure due to the ion density.

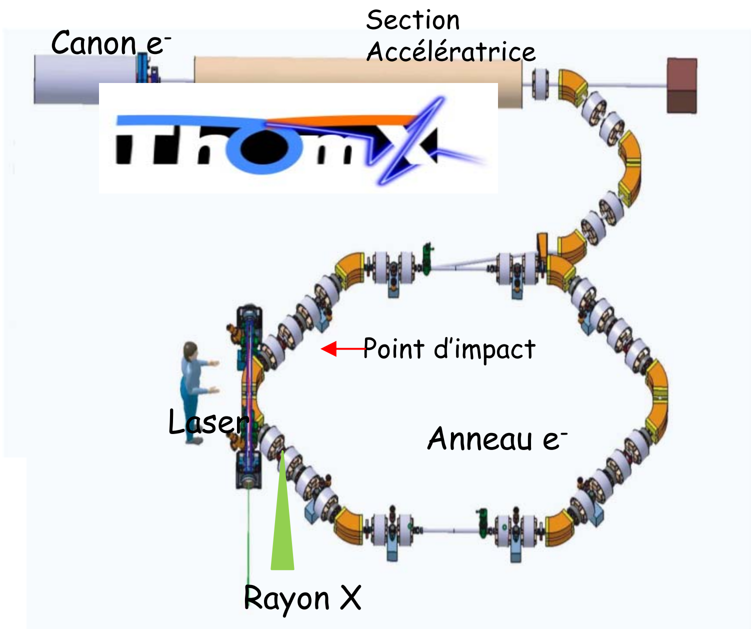
$$P_{ion} = \frac{I}{e} \cdot \frac{\eta^* \cdot k \cdot T}{\beta \cdot C \cdot \pi \cdot 2 \cdot \sigma_x \cdot \sigma_y}$$

Ionic pressure (mbar)



Time (sec)

At l' IP $\sigma_x=\sigma_y=0.07$ mm P≈ $2{*}10^{-9}$ mbar



Solutions:

Electrodes + gap between two injections (5μs)

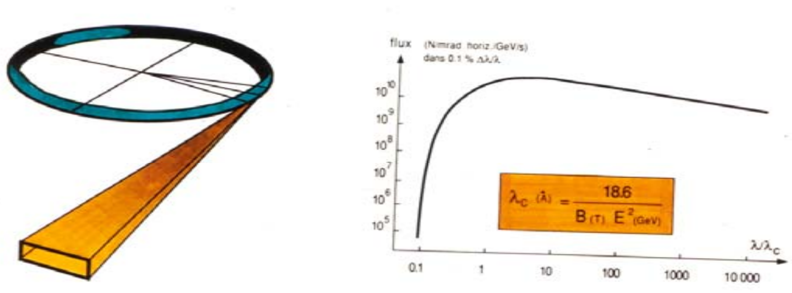
C. Bruni, J. Haissinski, T. Demma

Synchrotron radiation

Any charged particle undergoing acceleration, centripetal or longitudinal, produces radiation.

Main source on circular colliders

RAYONNEMENT SYNCHROTRON : DIPOLES



Emission vers l'avant dans un angle très faible $\alpha \frac{1}{E}$

Spectre blanc

Power loss

electron $P_0\,[\mathrm{W/m}] = 88.57 \dfrac{E[\mathrm{GeV}]^4}{2\pi\,\rho[\mathrm{m}]^2}\, I[\mathrm{mA}]$

proton $P_0\,[\mathrm{W/m}] = 7.79\ 10^{-12} \dfrac{E[\mathrm{GeV}]^4}{2\pi\,\rho[\mathrm{m}]^2}\, I[\mathrm{mA}]$

Critical energy

$$\text{Electrons}\ : \varepsilon_c[\mathrm{eV}] = 2.218\ 10^{3} \frac{E[\mathrm{GeV}]^3}{\rho[\mathrm{m}]}$$

$$\text{Protons}\ : \varepsilon_c[\mathrm{eV}] = 3.5835\ 10^{-7} \frac{E[\mathrm{GeV}]^3}{\rho[\mathrm{m}]}$$

Flux

$$\dot{\Gamma}[\mathrm{photons.m^{-1}.s^{-1}}] = 1.288\,10^{17} \frac{E[\mathrm{GeV}]}{\rho[\mathrm{m}]} I[\mathrm{mA}]$$

$$\dot{\Gamma}[\mathrm{photons.m^{-1}.s^{-1}}] = 7.017\,10^{13} \frac{E[\mathrm{GeV}]}{\rho[\mathrm{m}]} I[\mathrm{mA}]$$

synchrotron radiation

some examples

		Soleil	KEK-B		LEP			LHC	
			LER	HER	Inj.	1	2	Inj.	Col.
Particule		e^-	e^+	e^-	e^-	e^-	e^-	p	p
Courant	mA	500	2600	1100	3	3	7	584	584
Energie	GeV	2.75	3.5	8	20	50	96	450	7000
R. courbure	m	5.36	16.31	104.46	2962.96			2784.302	
Puissance	**W/m**	**14 030**	**20 675**	**5 820**	**0.8**	**30**	**955**	**0**	**0.2**
En. critique	**eV**	**8 600**	**5 800**	**11 000**	**6 000**	**94 000**	**660 000**	**0**	**44**
Flux	**photons/m/s**	**$3\ 10^{19}$**	**$7\ 10^{19}$**	**$1\ 10^{19}$**	**$3\ 10^{15}$**	**$7\ 10^{15}$**	**$3\ 10^{16}$**	**$7\ 10^{15}$**	**$1\ 10^{17}$**
Dose a 3000 h	photons/m	$4\ 10^{26}$	$8\ 10^{26}$	$1\ 10^{26}$	$3\ 10^{22}$	$7\ 10^{22}$	$3\ 10^{23}$	$7\ 10^{22}$	$1\ 10^{24}$

Photon stimulated desorption

photodesorption Yield η

$$\eta = \frac{\text{desorbed molecule}}{\text{Incident photons}}$$

→ material type, surface finish, energy and particle type, incidence angle, particule dose

Experimental determination

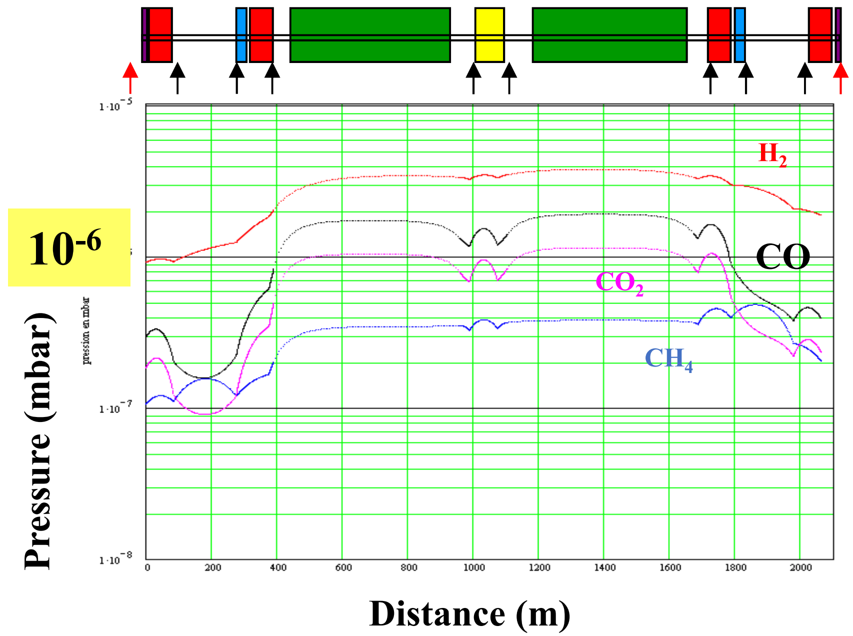
photodesorption Yield η at machine start-up

gas	η (mol/ph)
H_2	~ 1.10^{-3}
CH_4	~ 1.10^{-4}
Co	~ 5.10^{-4}
Co_2	~ 3.10^{-4}

For baked Cu 150°C and Ec = 4,5 Kev

Gröbner and all, JVSTA 12(3) 1994

the pressure distribution in Cell HER (SUPERB) with synchrotron radiation at machine start-up



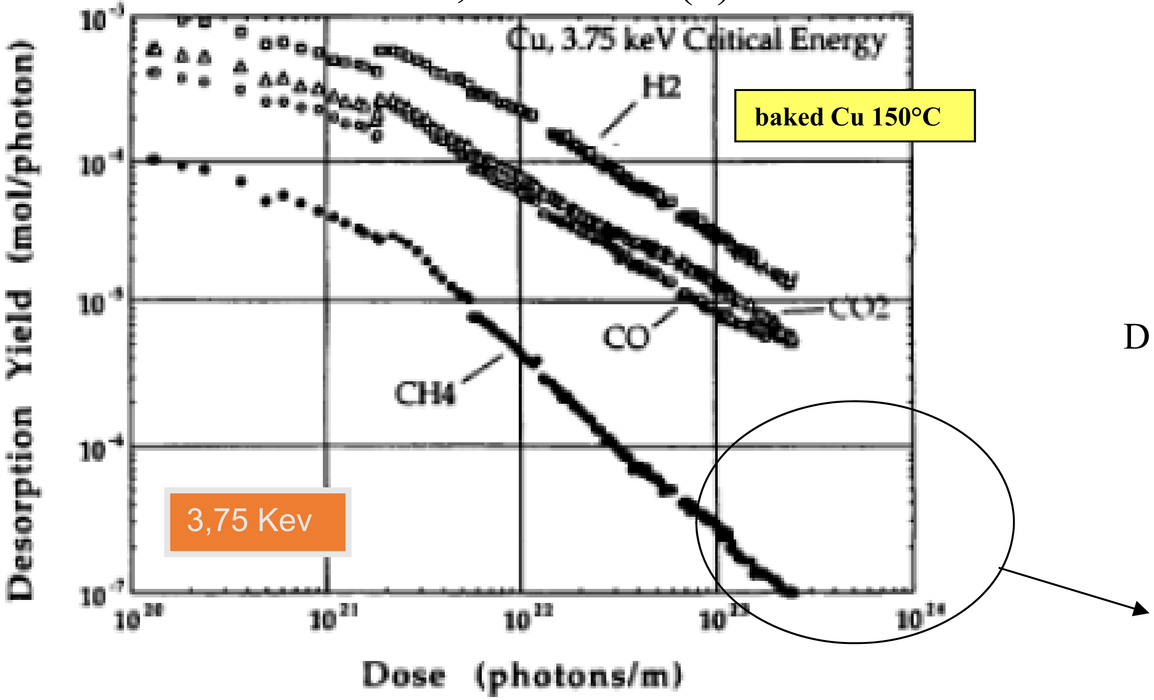
The static pressure increases by several orders of magnitude due to dynamic effects

photodesorption

Conditioning - Scrubbing

Surface conditioning according to the received dose

Gröbner and all, JVSTA 12(3) 1994



$$\eta = \eta_0 \cdot \left(\frac{D}{D_0}\right)^{-\alpha} \qquad \alpha = 0.84$$

After conditionning

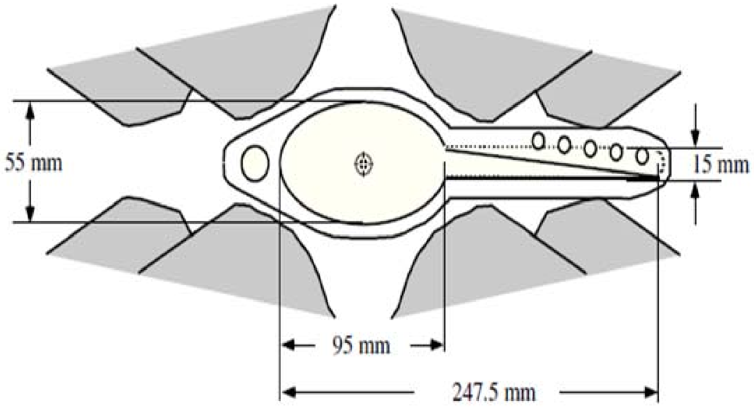
D = photon dose 10^{25} photons/m ~360 A.h

gas	η (mol/ph)
H_2	~ 6.10^{-7}
CH_4	~ 2.5.10^{-8}
Co	~ 2.5.10^{-7}
Co_2	~ 2.5.10^{-7}

Scrubbing but needed time

Photon stimulated desorption

Important implications for the design



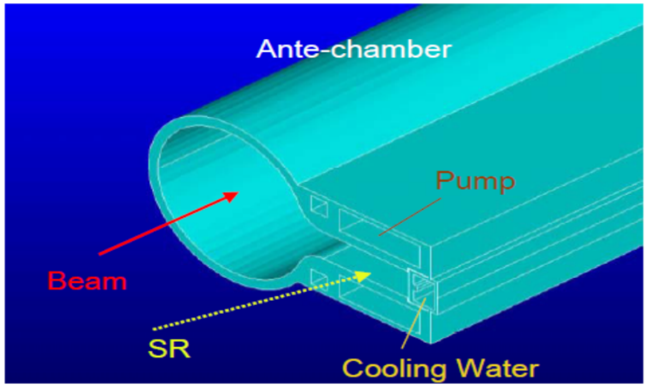
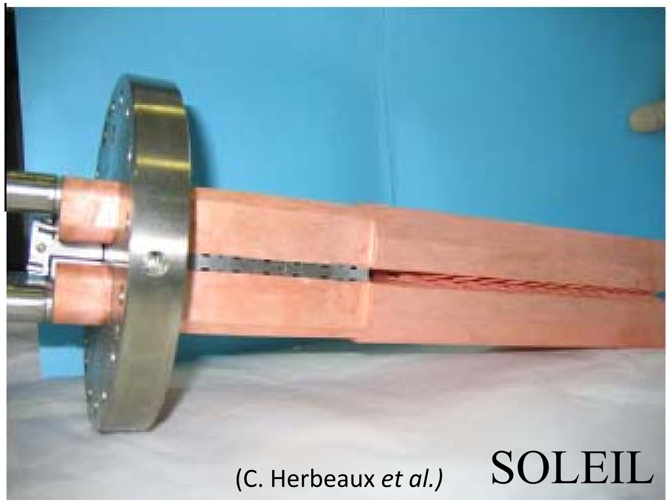


Figure 1: Typical structure of ante-chamber for the LER of Super-KEKB.



SOLEIL

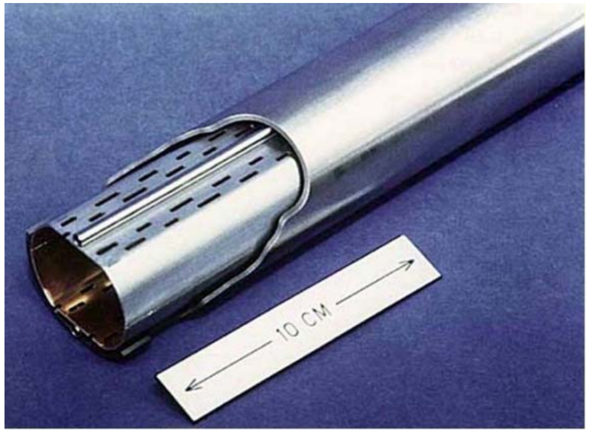
Puissance	**W/m**	**14 030**
En. critique	**eV**	**8 600**
Flux	**photons/m/s**	**$3\ 10^{19}$**

Absorbing power "crotch" : GLIDCOP copper cooled by water(256 W / mm2)

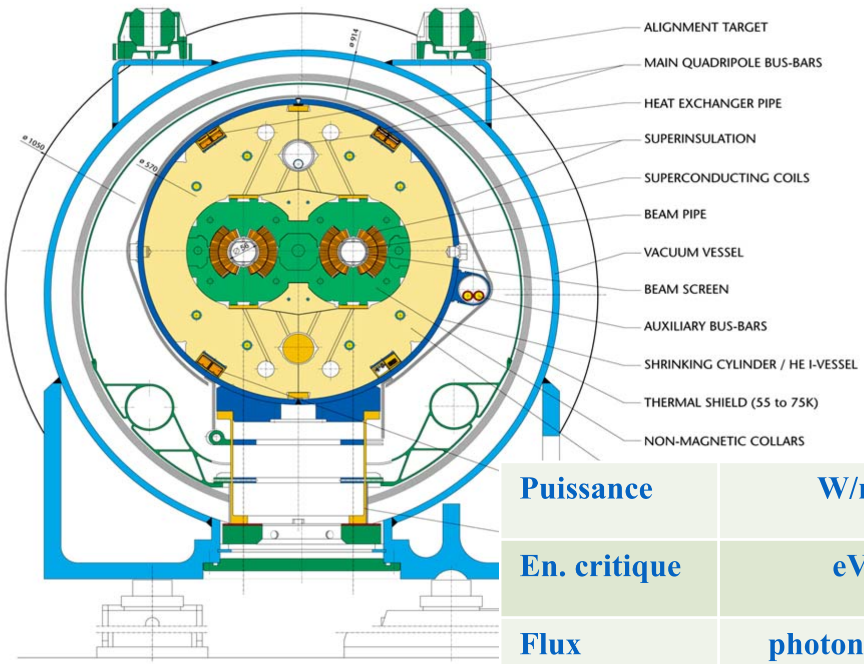
Photon stimulated desorption

LHC Dipole Vacuum System

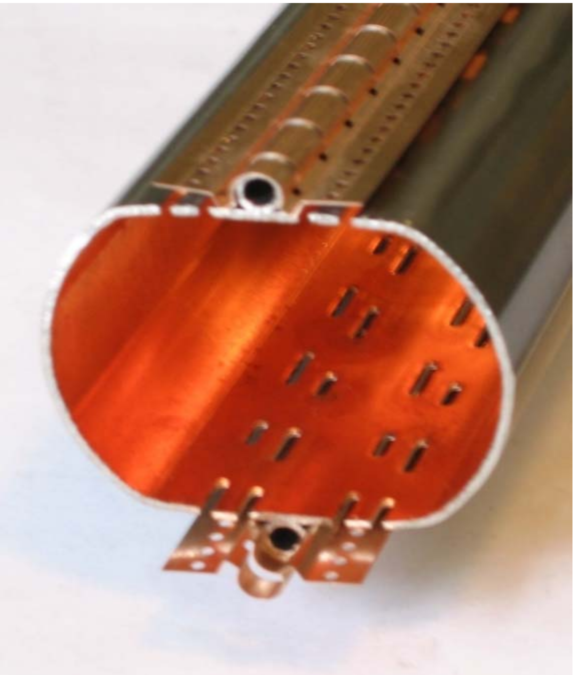
- Cold bore (CB) at 1.9 K which ensures leak tightness
- Beam screen (BS) at 5-20 K which intercepts thermal loads and acts as a screen



LHC DIPOLE : STANDARD CROSS-SECTION



Puissance	W/m	0.2
En. critique	eV	44
Flux	photons/m/s	$1\ 10^{17}$



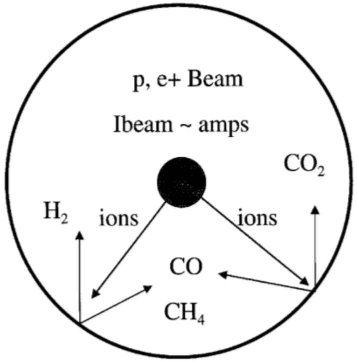
Courtesy N. Kos CERN AT/VAC

V. BAGLIN

Ion stimulated desorption

Positive charge beam

The mechanism: ionization of the residual gas by the beam
↓
Acceleration of these ions by the beam electric field (e +, p)
↓
The ions/surface impact creates a molecular desorption

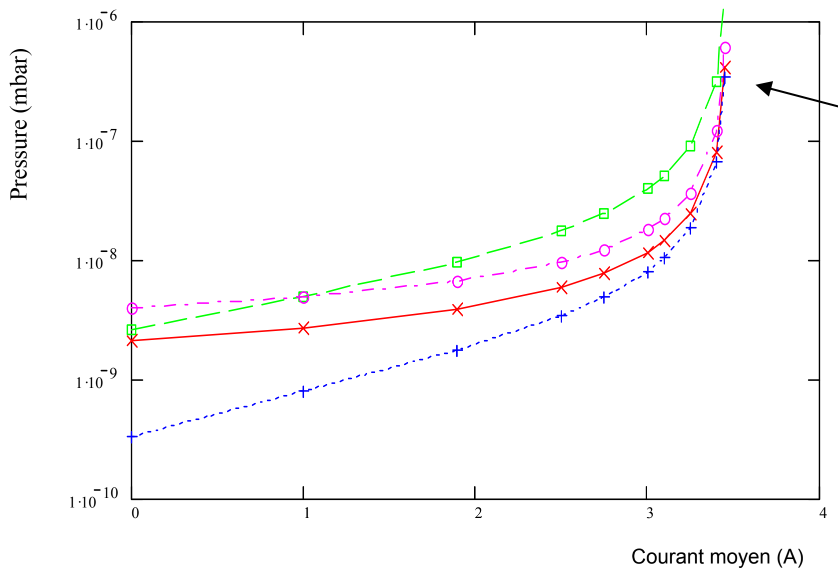


The important parameter

Rendement $\eta = \frac{\text{desorption molecular}}{\text{Incident ions}}$

flux: $\Gamma_{ion} \approx \sigma \frac{I}{e} \cdot \frac{\beta \cdot P}{k \cdot T}$

HER (SuperB) simulation



pressure divergence

$$I_{crit} \approx \frac{1}{\eta} \frac{eS}{\sigma}$$

Effectif Pumping speed

Cross section

(Avoid heavy gas)

- High current accelerators : ISR, SNS, LHC…

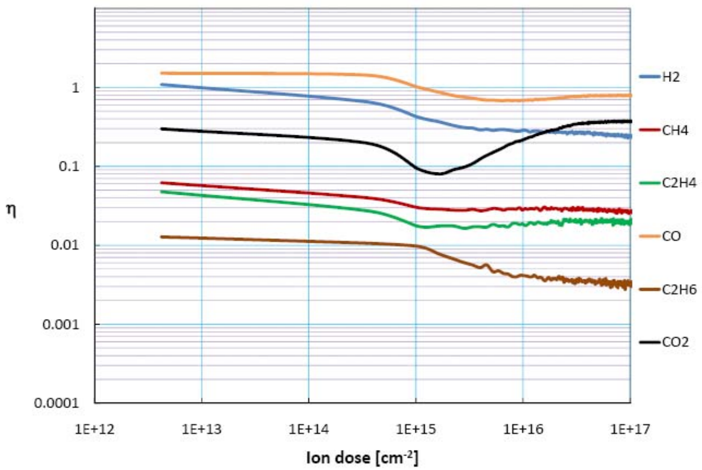
Ion stimulated desorption

Ionodesorption Yield η → material type, surface finish, energy and particle type, incidence angle, particle dose

Experimental determination

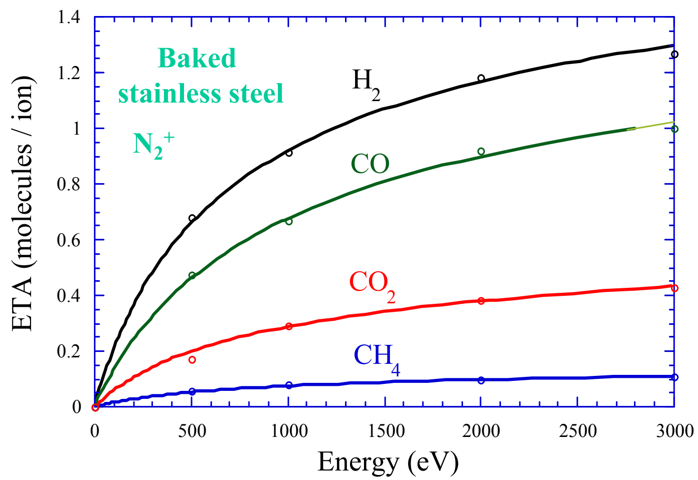
η versus ion dose

7 keV, Cu Baked, CO^+



G. Hulla, PhD Thesis, Vienna Tech. U, 2009

η versus energy



A.G. Mathewson, CERN ISR-VA/76-5

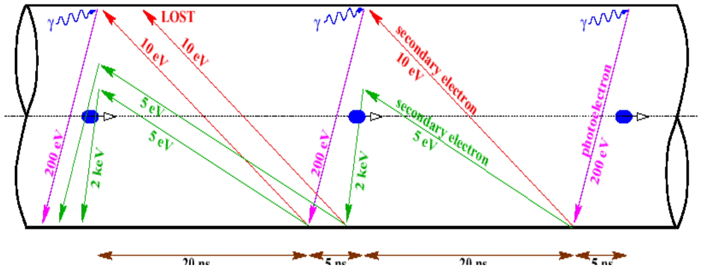
LHC : ion dose ~ 3 10^{15} ions/(cm2.an)

Inefficient scrubbing !!

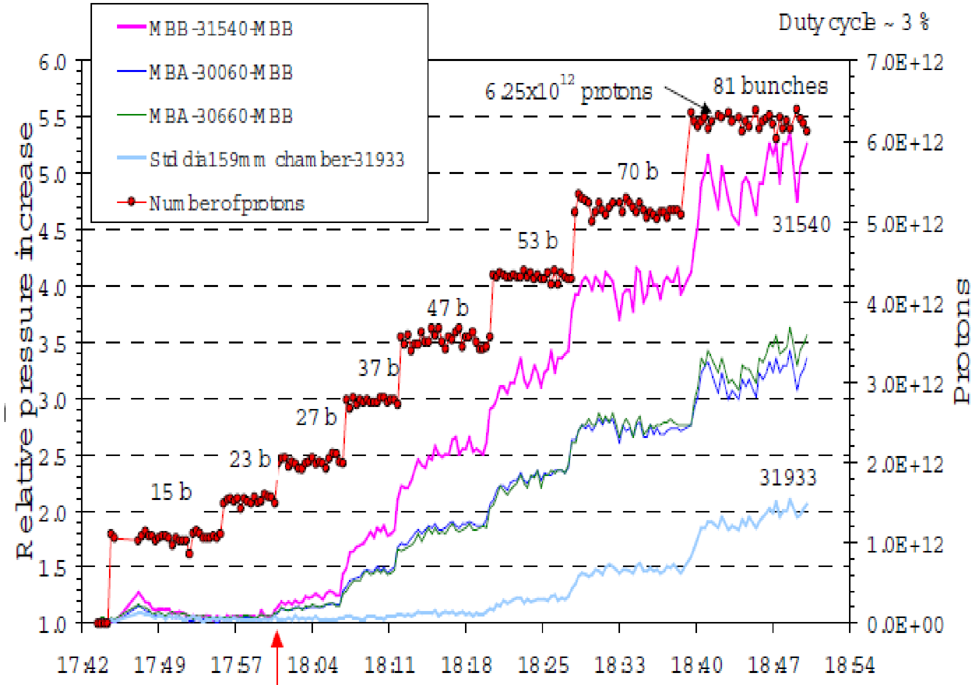
Electron-Cloud / Electron Stimulated Desorption

KEKB, PEP II, SPS ~ année 2000
RHIC, LHC

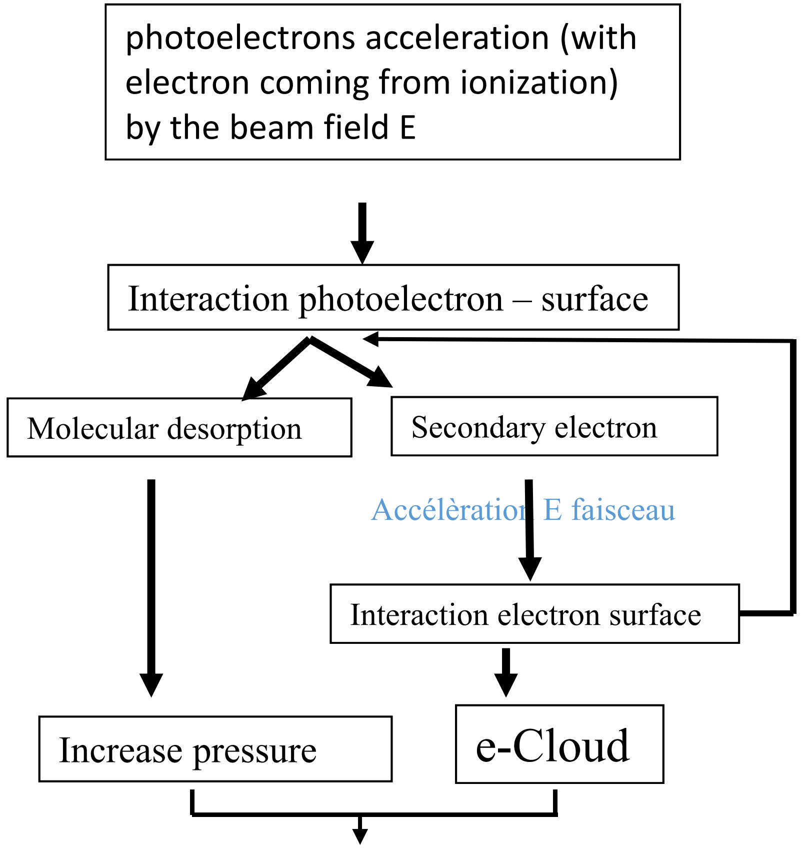
The mechanism:



F. Ruggiero *et al.*, LHC Project Report 188 1998, EPAC 98



J.M. Jimenez *et al.*, EPAC 2000, Vienna, Austria



Increase emittance and beam loss, heat load, decrease luminosity

Electron-Cloud / Electron Stimulated Desorption

An important phenomenon for positive charges beam, for high current and for short bunch spacing

Main parameters:

- Beam structure(size,time between bunch)
- bunch/charge
- chamber size and geometry
- secondary electron yeld (SEY)
- photo-electrons rate
- photons /electrons reflected
- electron stimulated desorption (ESD)

↓ reduction

Some Solutions

material (coating), surface finish, scrubbing,

Cleaning electrodes, solenoidal field,

Geometry chamber (antichamber)

Electron-Cloud / Electron Stimulated Desorption

Surface conditionning by electron impingement

(Scrubbing)

Reduction ESD and SEY

Electron Stimulated Desorption (ESD)

ESD versus e- dose

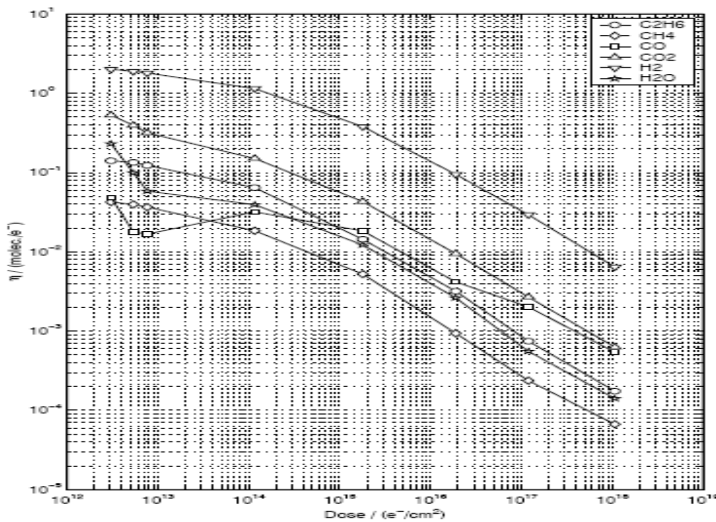
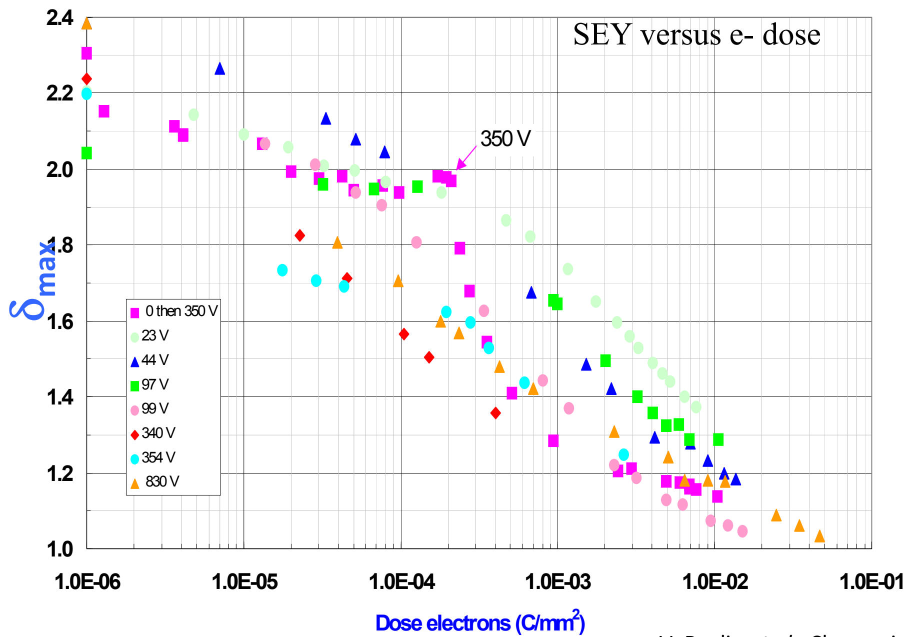


Figure 3: Effect of the electron dose on the electron induced desorption yield of an unbaked copper sample. The electron energy during bombardment and measurement was 300 eV.

G. Vorlaufer *et al.*, CERN VTN, 2000

Secondary electron yeld (SEY)

$$\text{SEY} = \frac{\text{number of emitted electrons (secondary)}}{\text{number of impinging electrons (primary)}}$$



V. Baglin *et al.*, Chamonix, 2001

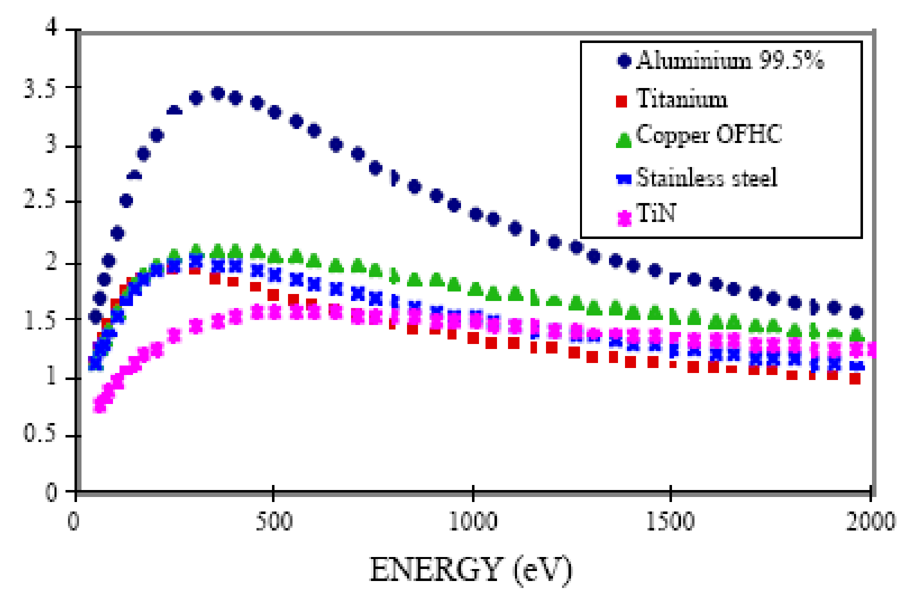
Carbone layer on surface (AES, XPS,..)

Scrubbing but needed time

Electron-Cloud / Electron Stimulated Desorption

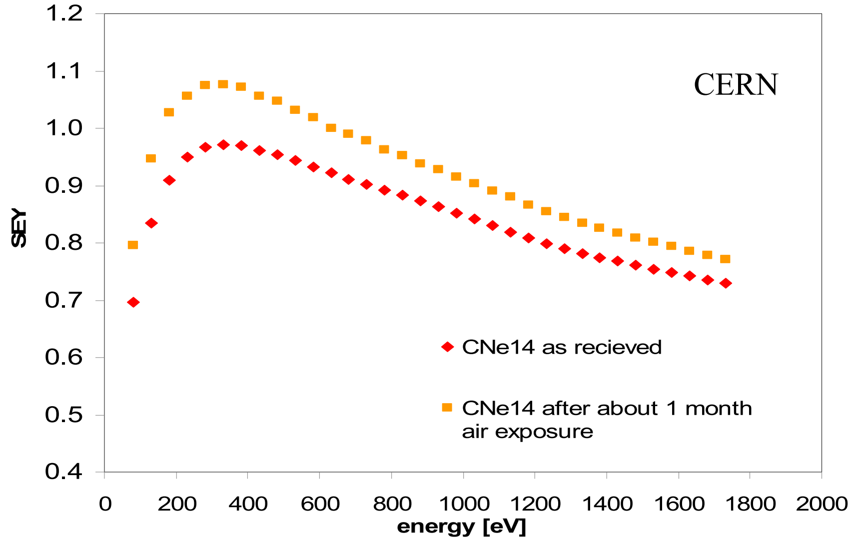
SEY Reduction

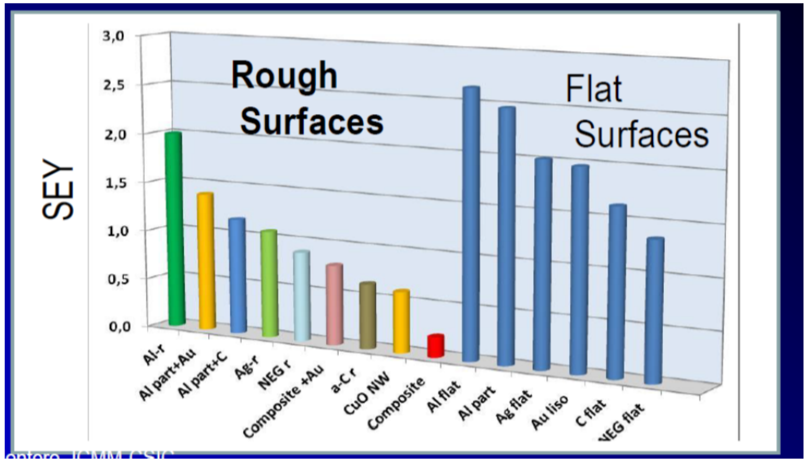
Material and relief surface



New

Amorphe carbone coating





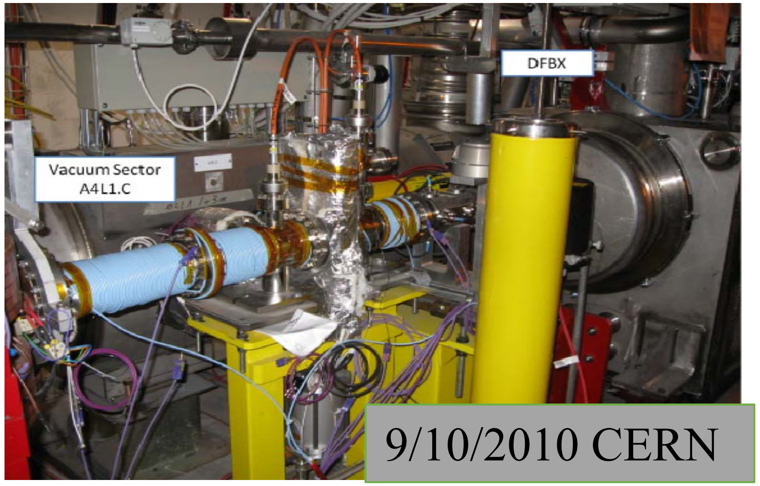
Coating TiN, TiZrV, amorphe C coating on vacuum chamber

Isabel Montero, ICMM-CSIC (AEC 2012)

Electron-Cloud / Electron Stimulated Desorption

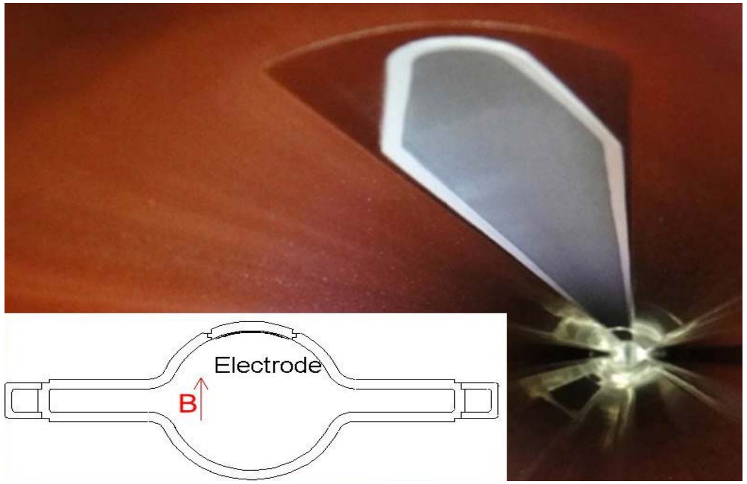
Other solution for e-Cloud decrease

External solenoid on chamber



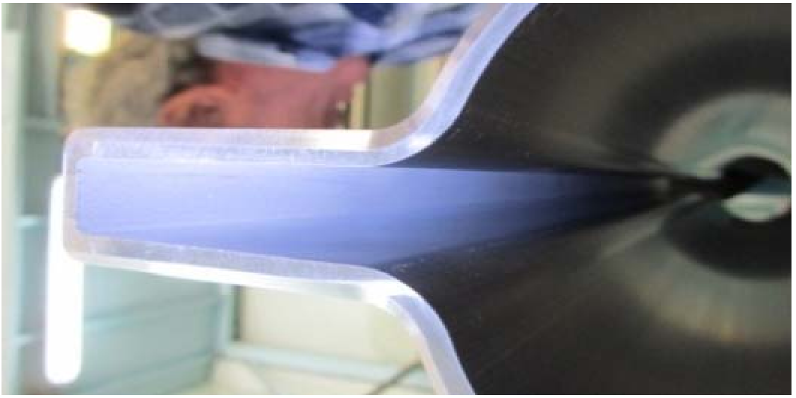
9/10/2010 CERN

Clearing electrodes

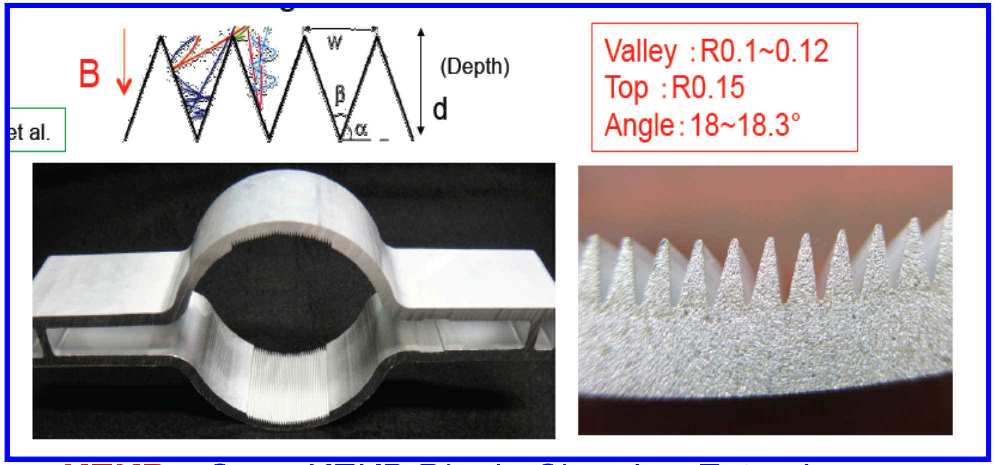


Y. Suetsugu SuperKEKB

Antichamber and Rough surface at the side wall (Ra ~20) reduces the photon reflection.



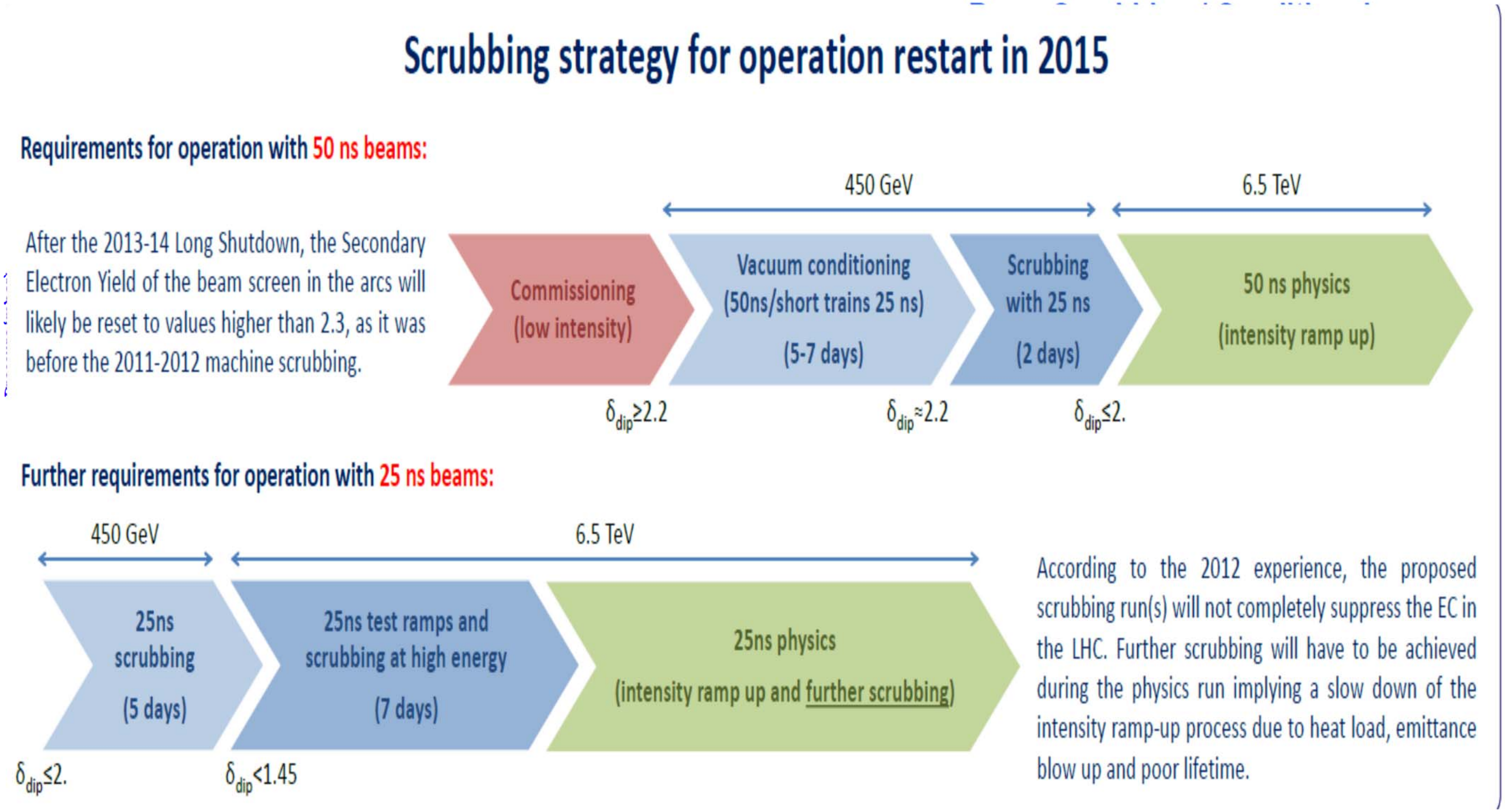
antichamber, grooves and coating TiN



Y. Suetsugu SuperKEKB SuperKEKB Dipole Chamber Extrusion

Electron-Cloud / Electron Stimulated Desorption

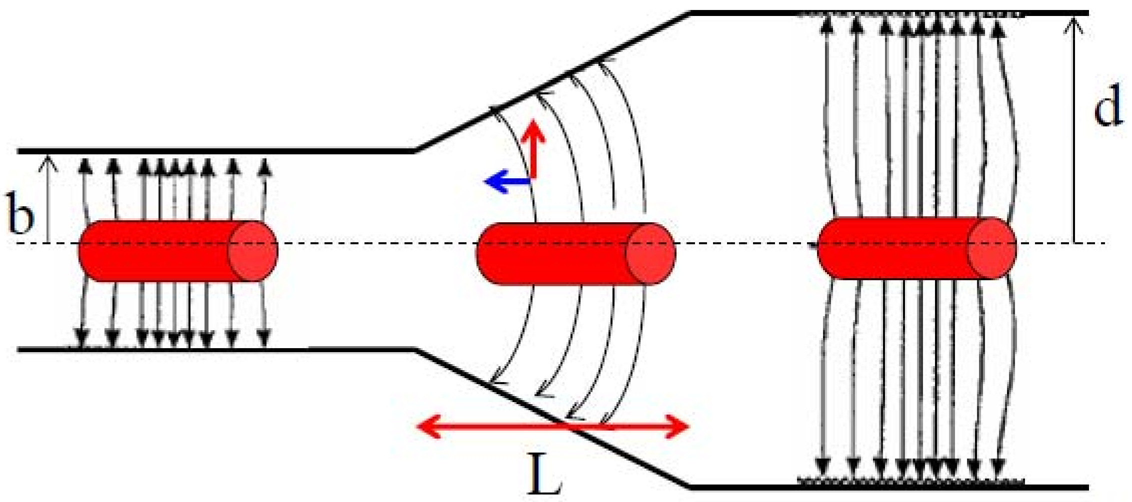
LHC



Other sources of instability beam:

Electric field Interaction -surface

Nonzero Impédance of the chamber



M. Ferrario – CAS Baden 2005

Accentuate by section changes, discontinuity ..

Power dissipated on the surface

Molecular desorption

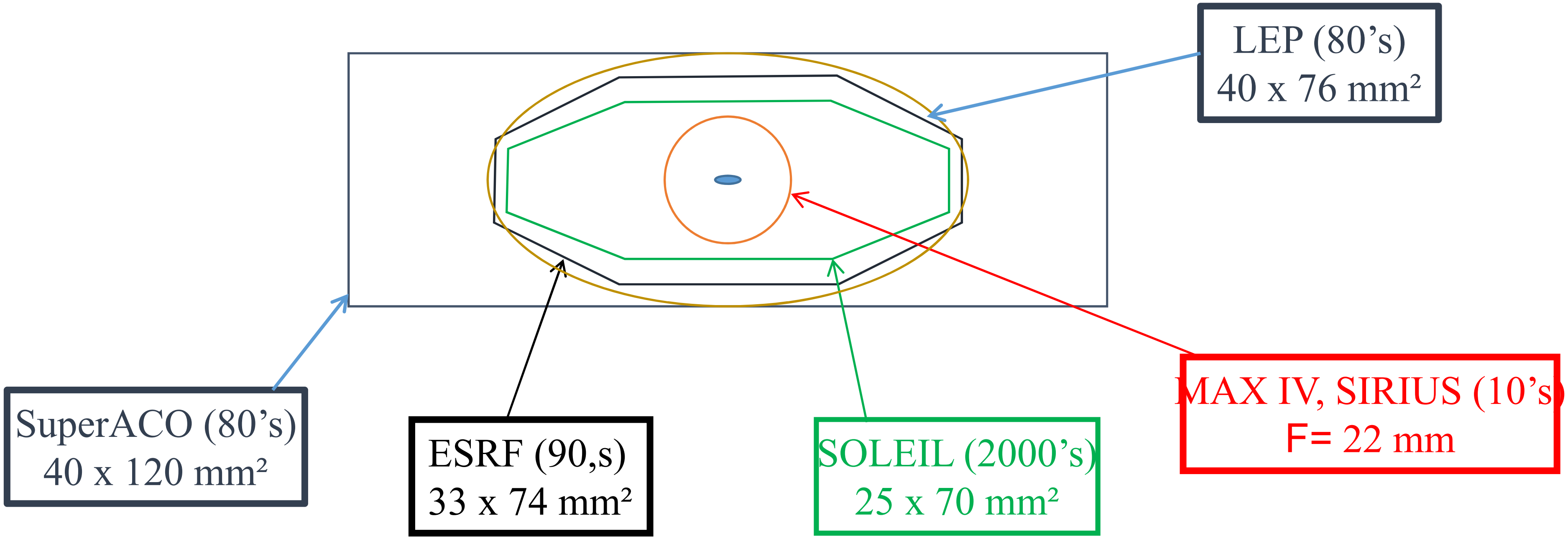
Beam instability

Evolution vacuum technology

size evolution of vacuum chambers on Accelerators

Size vacuum chambers are constrained by the beam of performance expected by the magnetic system including:

- Strong focus therefore reduces throat circle
- Low distance between the magnets.

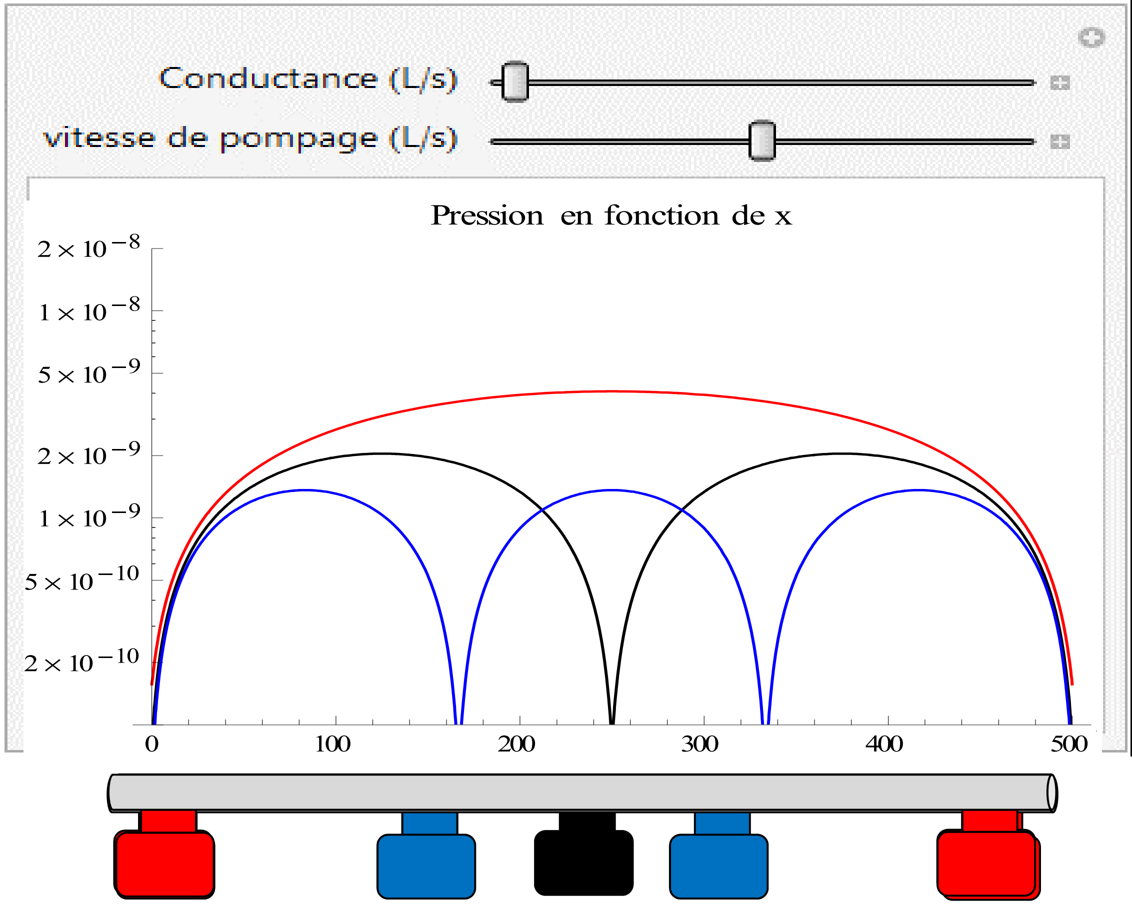


C. Herbeaux SFP – Journées des accélérateurs, Roscoff, SFP 2013

Evolution vacuum technology

Consequences : size room more and more small

Significant decrease in conductance and increasing the maximum pressure



$$P_{mean} = A \cdot \tau \cdot L \left(\frac{1}{12C} + \frac{1}{S} \right)$$

$$P_{\max} = A \cdot \tau \cdot L \left(\frac{1}{8C} + \frac{1}{S} \right)$$

τ outgassing rate   C conductance

A circonference of chamber

if S>> 8C then $P_{max} \sim A\tau L/(8C)$

Decrease of Pmean and Pmax is limited by the conductance C :

- Reduce outgassing rate (τ) and the stimulated desorption

- Reduce length L

distributed pumping

Evolution vacuum technology

distributed pumping

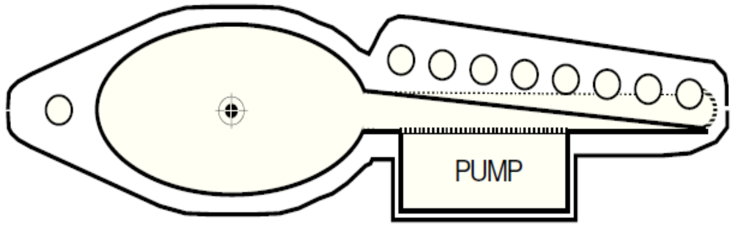
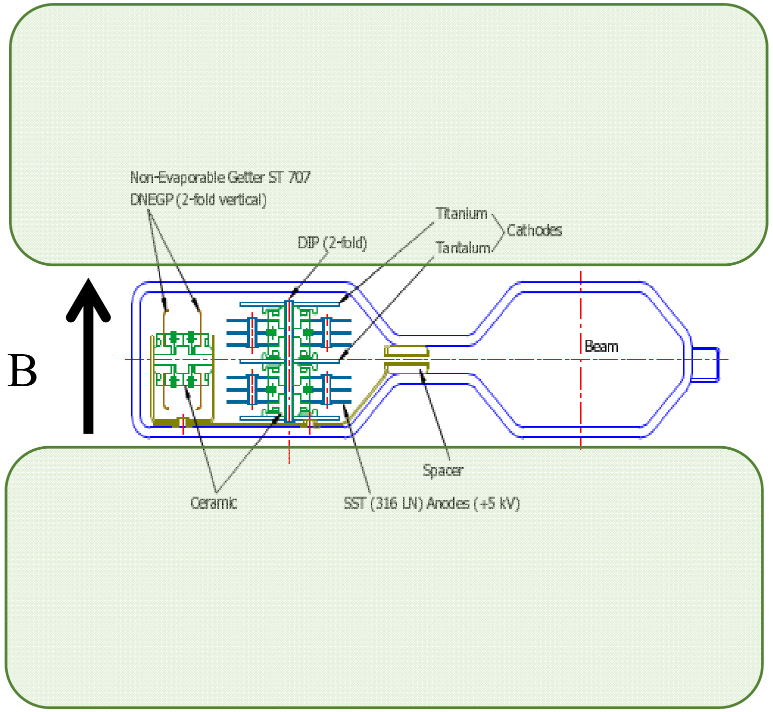
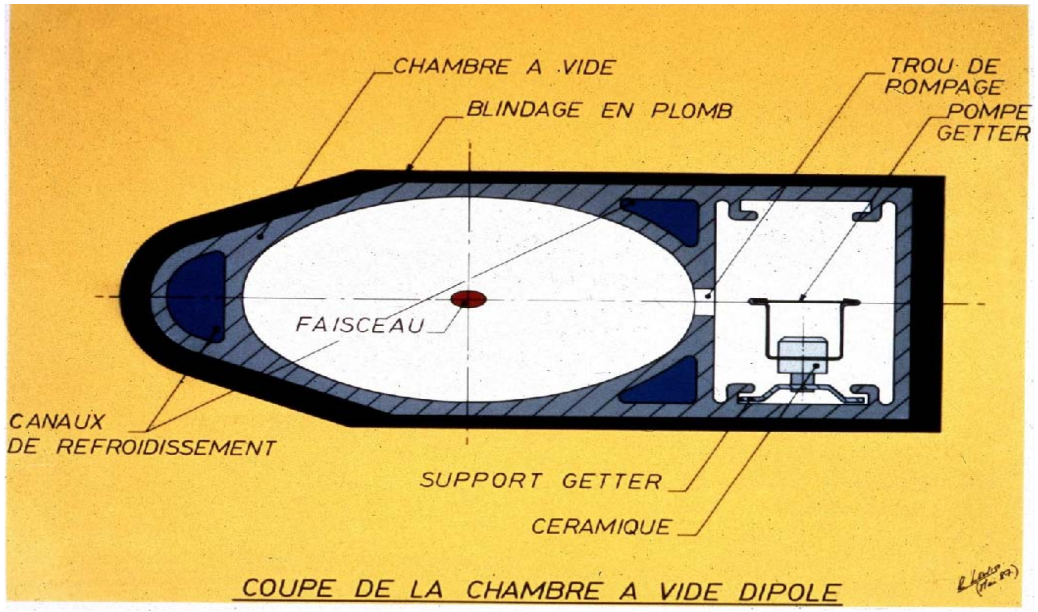
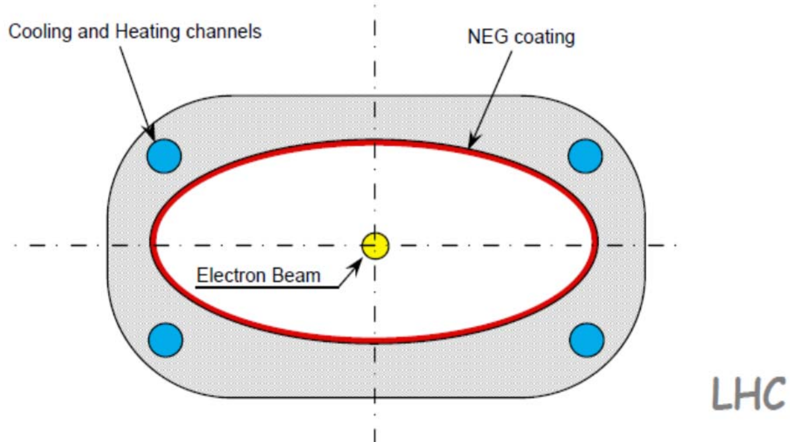


Figure 3-108. *LER dipole vacuum chamber concept. Inside dimensions match those of Fig. 3-107.*





LEP Design (CERN LEP Vacuum group)



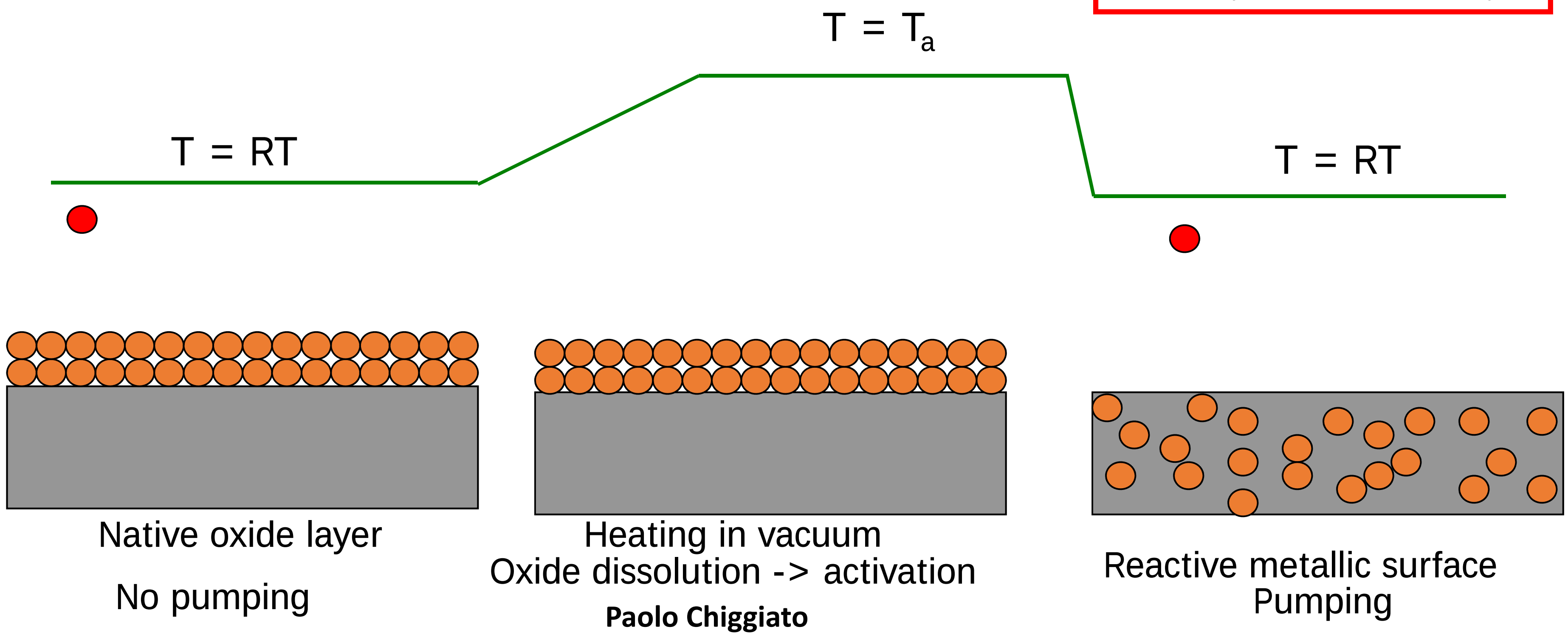
Non evaporable Getter (NEG)

Principle

coating of metal alloy (NEG) on the walls of vacuum chambers or on a strip

- **coating Zr-Al, Zr-V-Fe, Ti-Zr-V, ….**
- **Ta activation temperature**

The alloy becomes a Pump!



Paolo Chiggiato

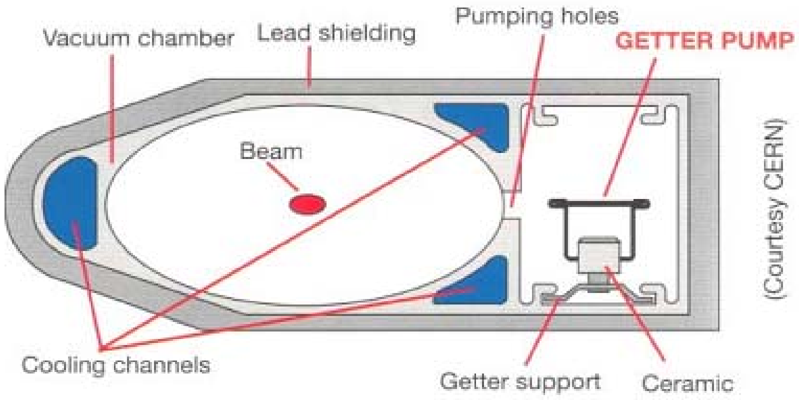
CERN European Organization for Nuclear Research

NEG strips

St101 NON-EVAPORABLE GETTER (Zr Al)
activation temperature at 700°c

St707 NON-EVAPORABLE GETTER (Zr 70-V 24.6-Fe 5.4 wt%)
activation temperature at 450°c

NEG materials are embedded in a constantan ribbon that is heated by the Joule effect



LEP – (CERN) 24 km de ruban installés
P< 10^{-11} mbar

The high temperature activation NEG can generate mechanical stresses in the vacuum chamber.

Need to have an antechamber

C. Herbeaux SFP – Journées des accélérateurs, Roscoff, SFP 2013

NEG strips

Design and construction of the SuperKEKB vacuum system

Yusuke Suetsugu,[a] Ken-ichi Kanazawa, Kyo Shibata, Takuya Ishibashi, Hiromi Hisamatsu, Mitsuru Shirai, and Shinji Terui
High Energy Accelerator Research Organization (KEK), Tsukuba, Ibaraki 305-0801, Japan

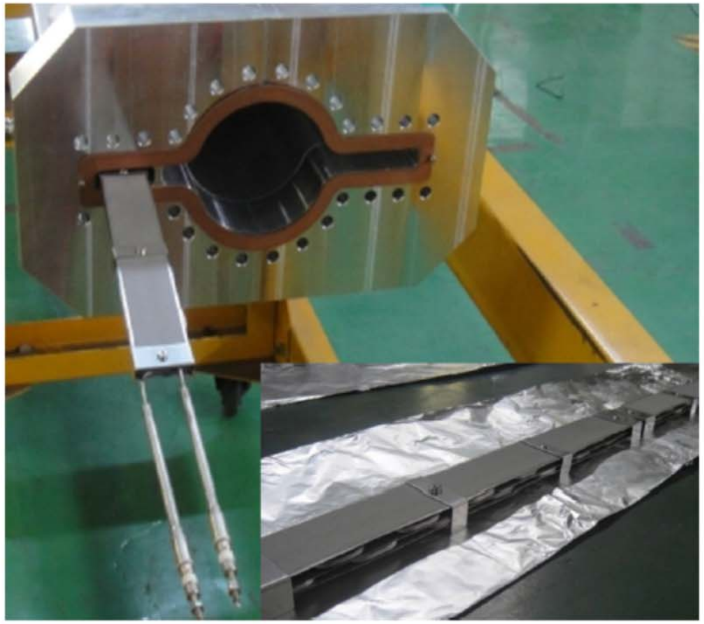


FIG. 4. (Color online) Multilayered NEG strips for the antechamber.

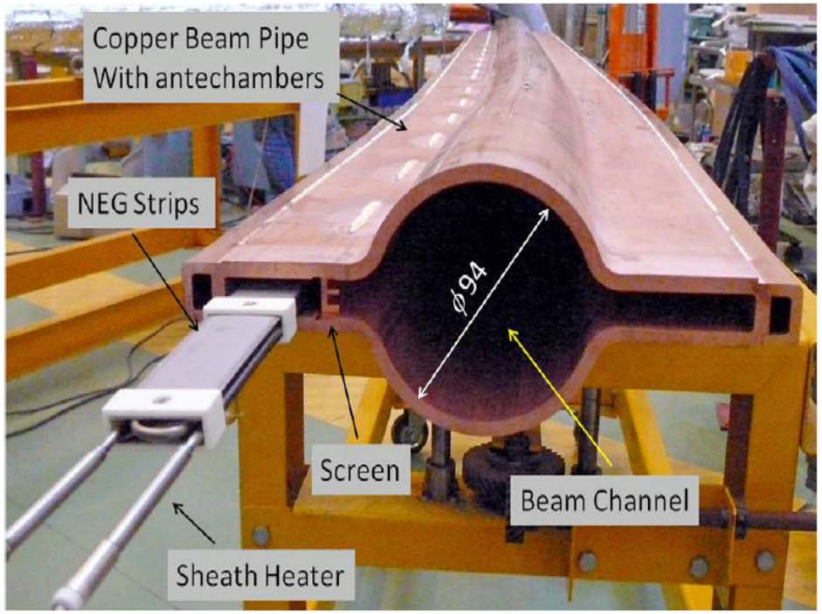


Fig. 1. Example of a beam pipe with antechambers and distributed pumps.

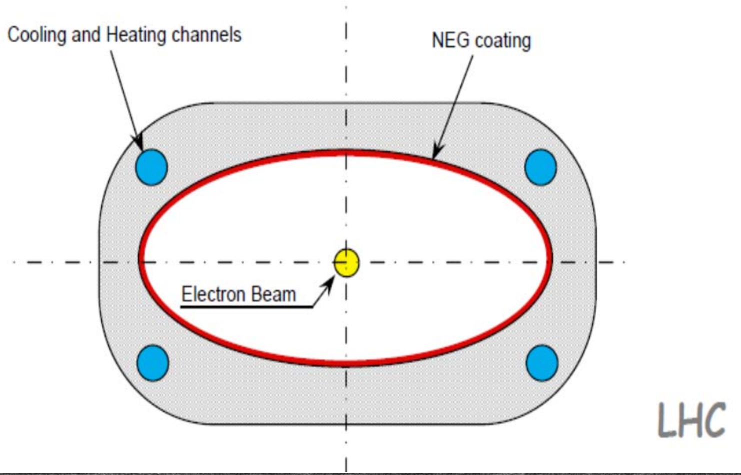
St707 NON-EVAPORABLE GETTER

J. Vac. Sci. Technol. A, Vol. 30, No. 3, May/Jun 2012

NEG coating in vacuum chamber

- Titane Zirconium Vanadium coating
- Low activation temperature Ta=180°C

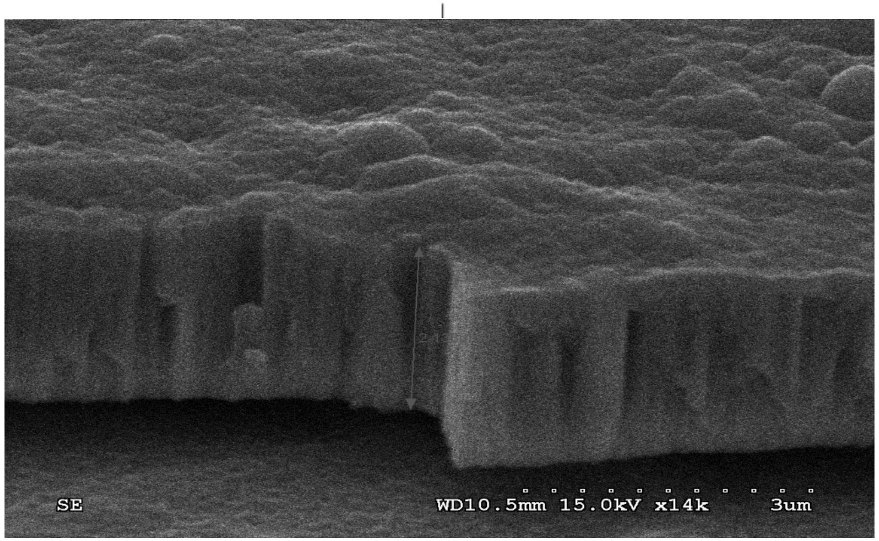
surface of vacuum chamber becomes a pump!!!



SOLEIL: NEG 60 % of the circumference

LHC : 6 km in warm part

MAX IV: 95% of the circumference



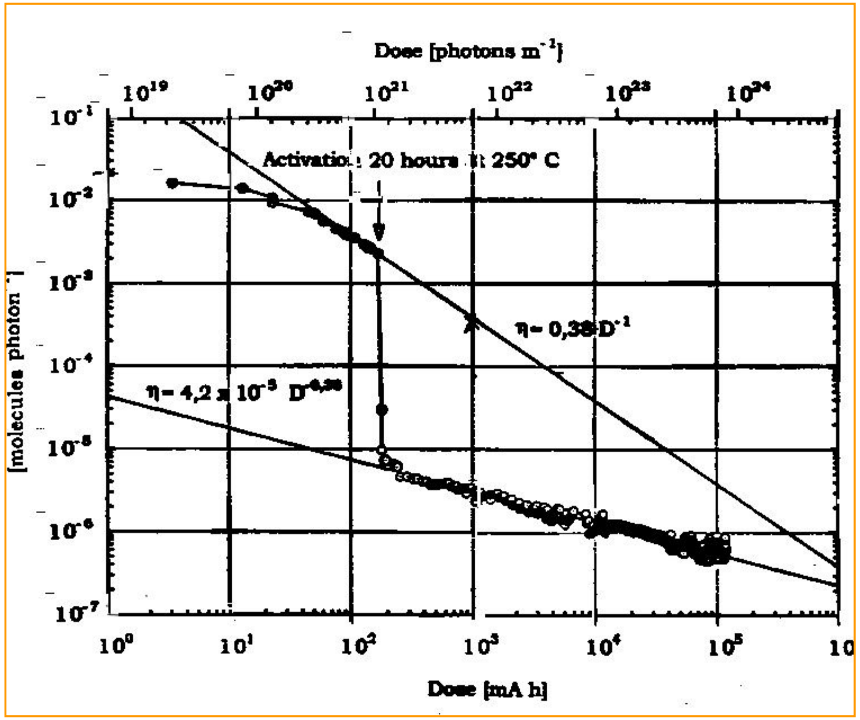
Coating at LAL (~2 µm)

NEG coating-vacuum performances

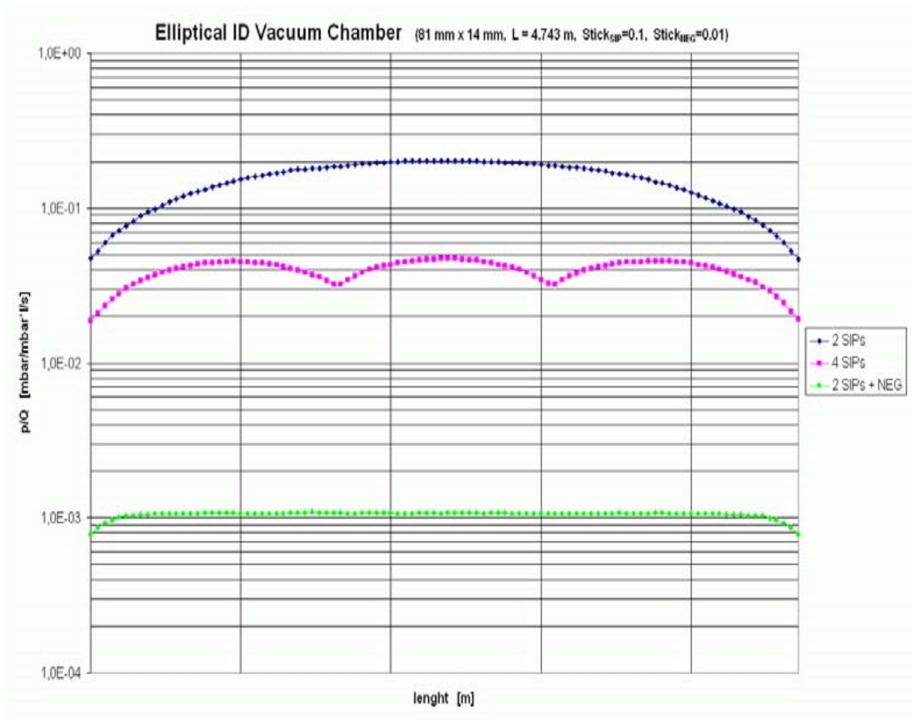
Titane ZirconiumVanadium coating

Electron and photon stimulated desorption photons (ESD and PSD) are reduced

A low secondary electron yield (SEY)



P. Chiggiato, R. Kersevan / Vacuum 60 (2001) 67-72



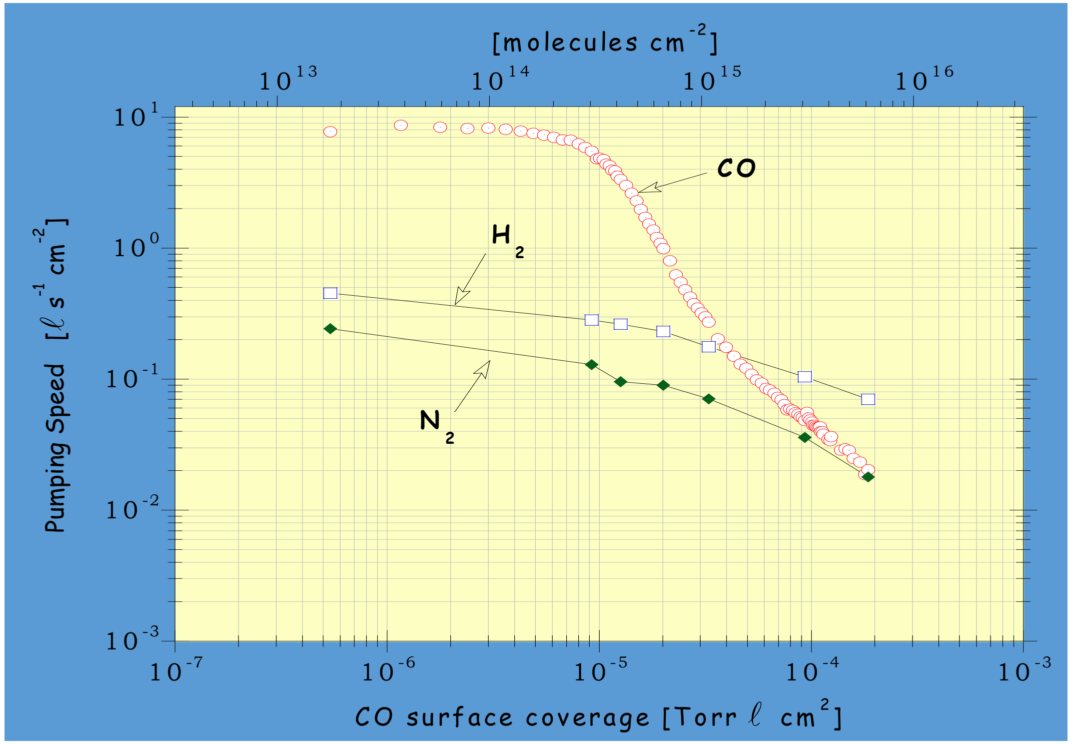
NEG coating-vacuum disadvantage

Titane ZirconiumVanadium coating

Selective pumping speed

(No pumping of rare gas, CH_4)

saturation effect



P. Chiggiato, R. Kersevan / Vacuum 60 (2001) 67-72

Conclusion

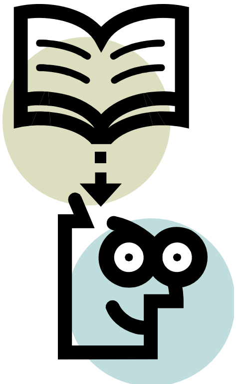
Trend: High luminosity accelerators (involves small-sized beams, high current and a high repetition frequency).

Many beams interactions, residual gas and surface will generate induced outgassing sources and impact the shape and the beam energy

Reduction of induced outgassing sources — Geometry, coating, surface condition, scrubbing,…..

Increase the effective pumping speed — Distributed pumping

NEG strips — Neg coating (TiZrV)

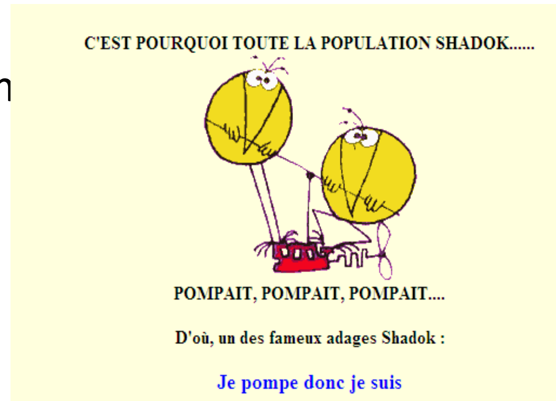


Some references

- Cern Accelerator School, Vacuum technology, CERN 99-05
- Cern Accelerator School, Vacuum in accelerators, CERN 2007-03
- Scientific foundations of vacuum technique, S. Dushman, J.M Lafferty.
J. Wiley & sons. Elsevier Science.
- Vacuum Technology, A. Roth. Elsevier Science.
- Jacow
- L'ultra vide des grands instruments – V. Baglin Gif-sur-Yvette - 22 septembre2009

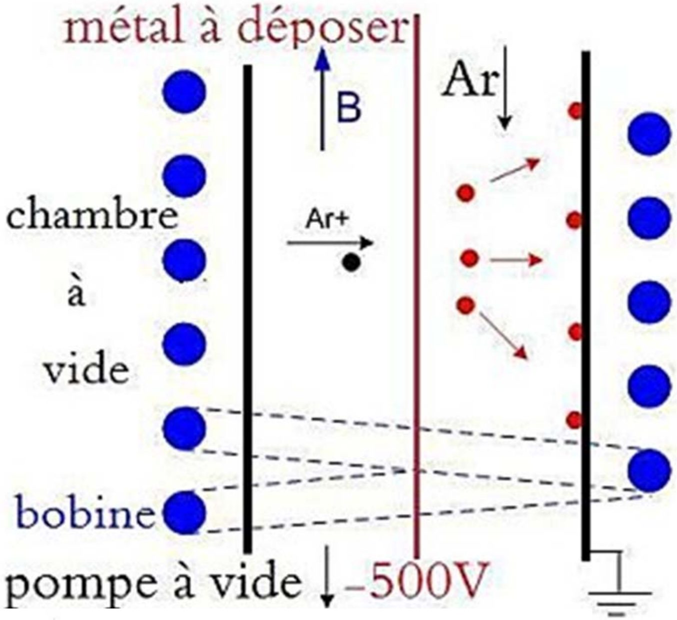
Journals

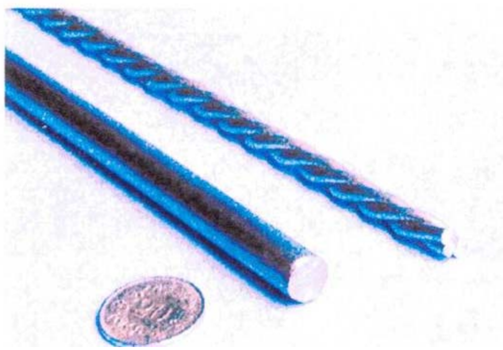
- Journal of vacuum science and technology
- Vacuum
- Physical review special topics Accelerators and Beam

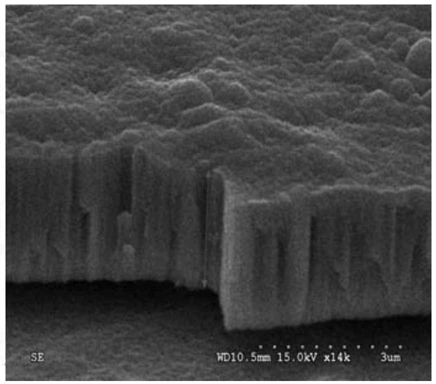


Le dépôt NEG

La pulvérisation cathodique magnétron







Paramètres de dépôt

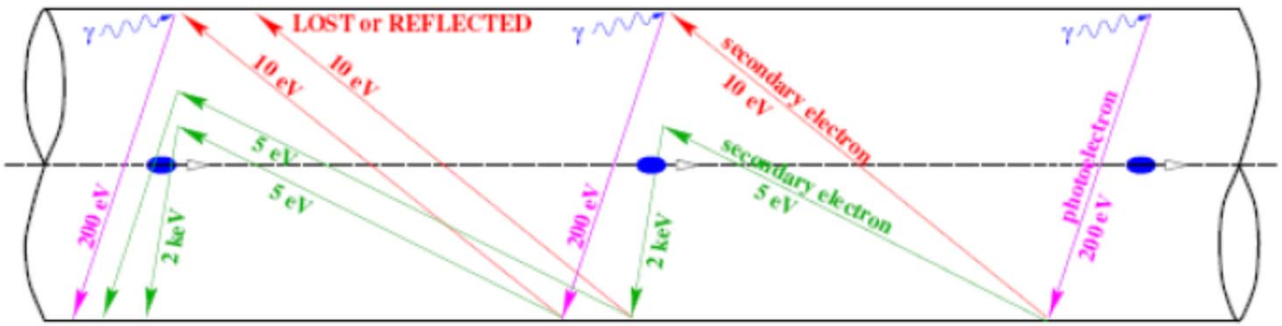
B = 100 G

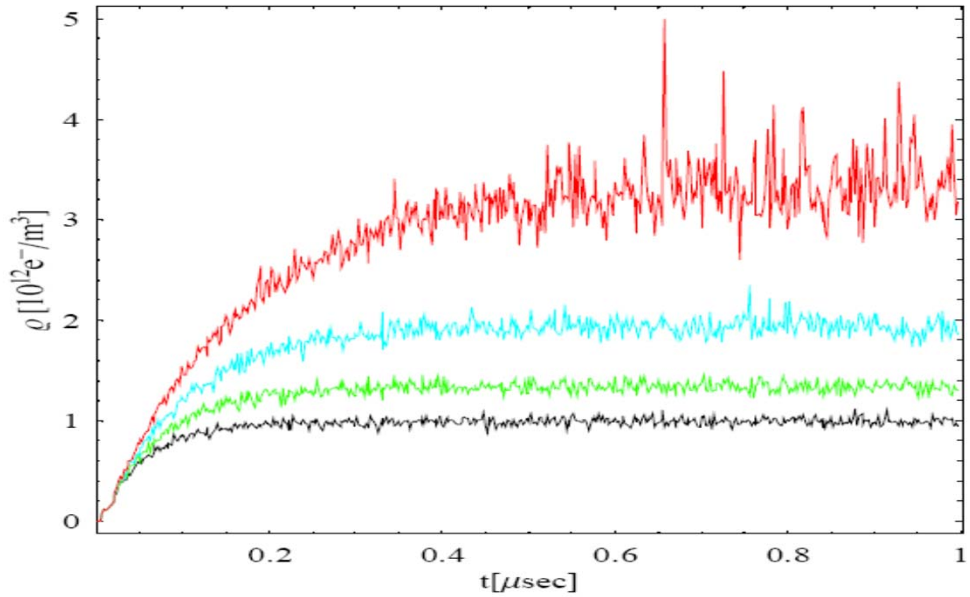
V = - 500 V

Pression Krypton : 2 10^{-2} mbar

Vitesse de dépôt : 1 Å/s

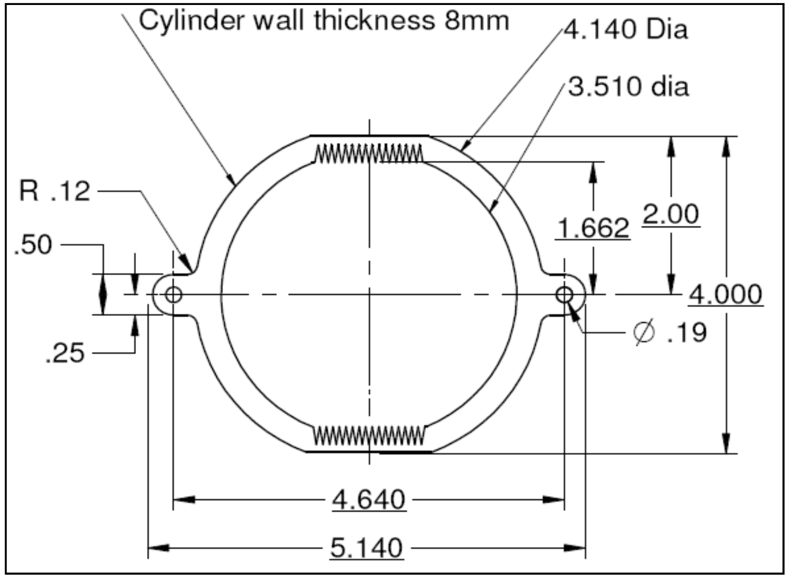
Electron Cloud Effects



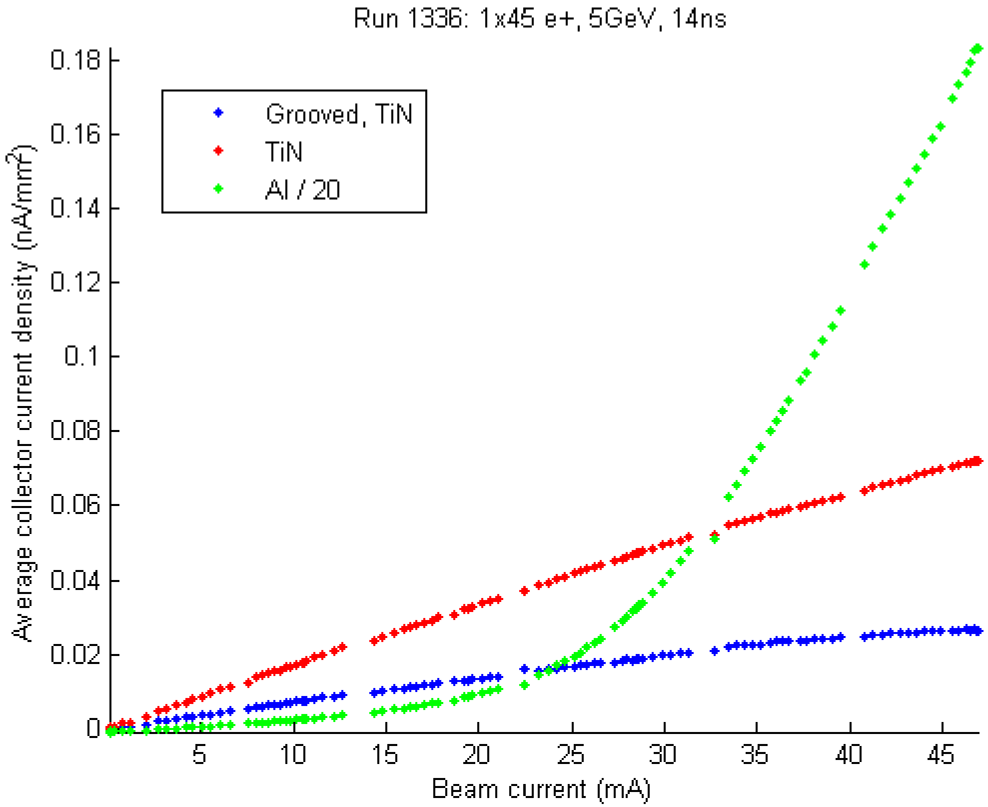


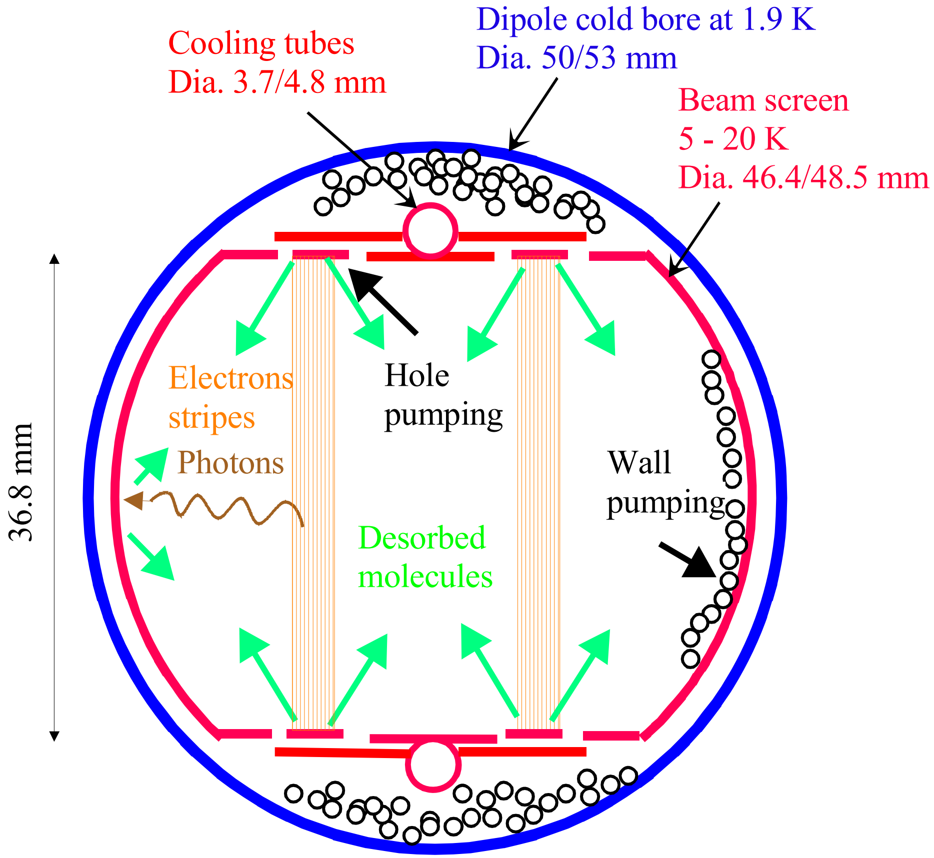
95% prot.

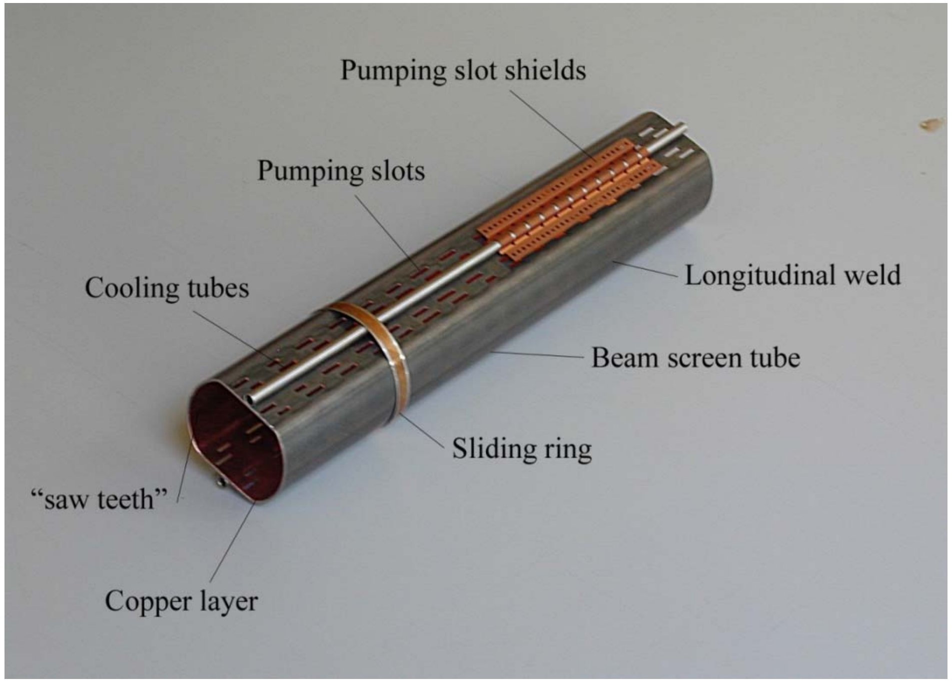
δmax=1
δmax=1.1
δmax=1.2
δmax=1.3



M. Pivi and L. Wang design, SLAC




Cooling tubes
Dia. 3.7/4.8 mm
Dipole cold bore at 1.9 K
Dia. 50/53 mm
Beam screen
5 - 20 K
Dia. 46.4/48.5 mm
36.8 mm
Electrons stripes
Photons
Hole pumping
Desorbed molecules
Wall pumping


Pumping slot shields
Pumping slots
Cooling tubes
Longitudinal weld
Beam screen tube
Sliding ring
“saw teeth”
Copper layer

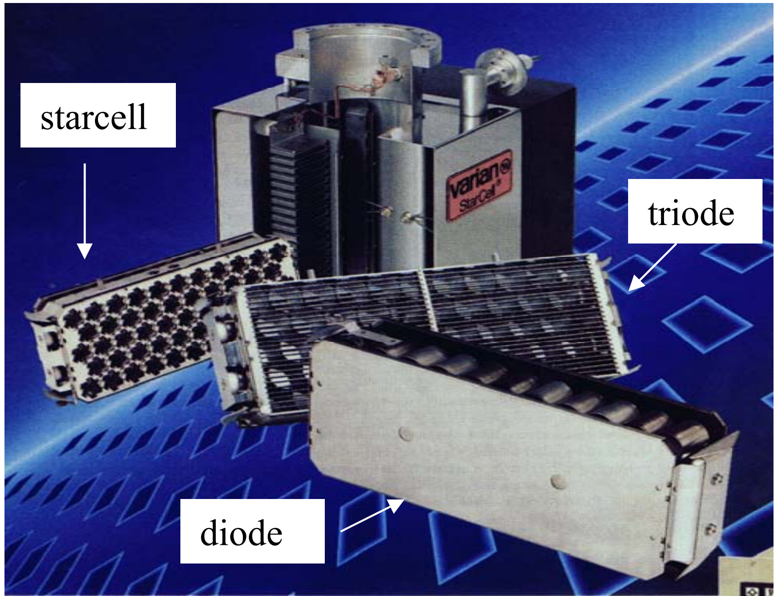
POMPES IONIQUES

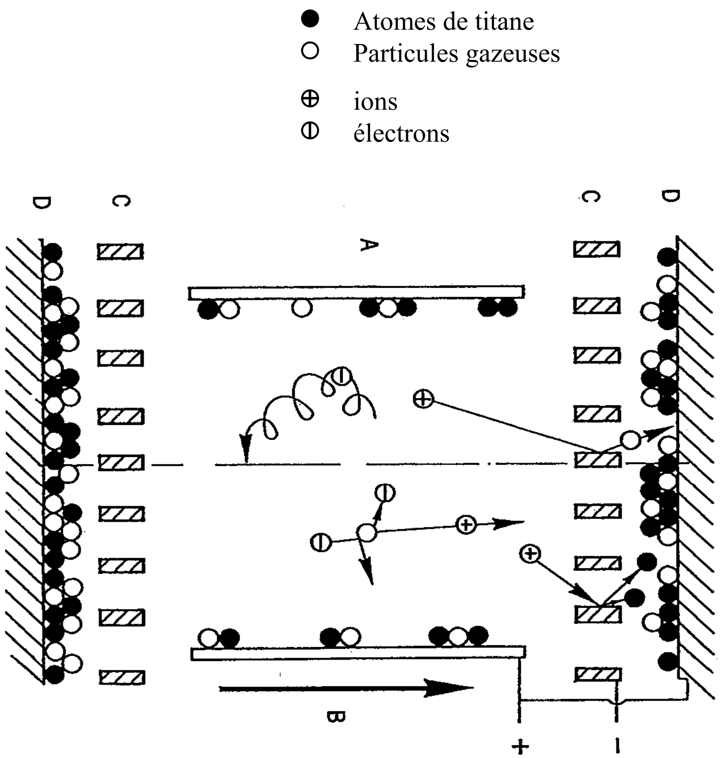
Trois phénomènes de pompage :

- par chimisorption → effet Getter (gaz actifs, CO, CO2, H2, N2, O2,..)
- par diffusion (principalement H2)
- par physisorption → enterrement (unique pompage pour les gaz rares)

Principalement deux configurations:

- Pompes ioniques Diodes (et noble diode)
- Pompes ioniques triodes (et starcell)





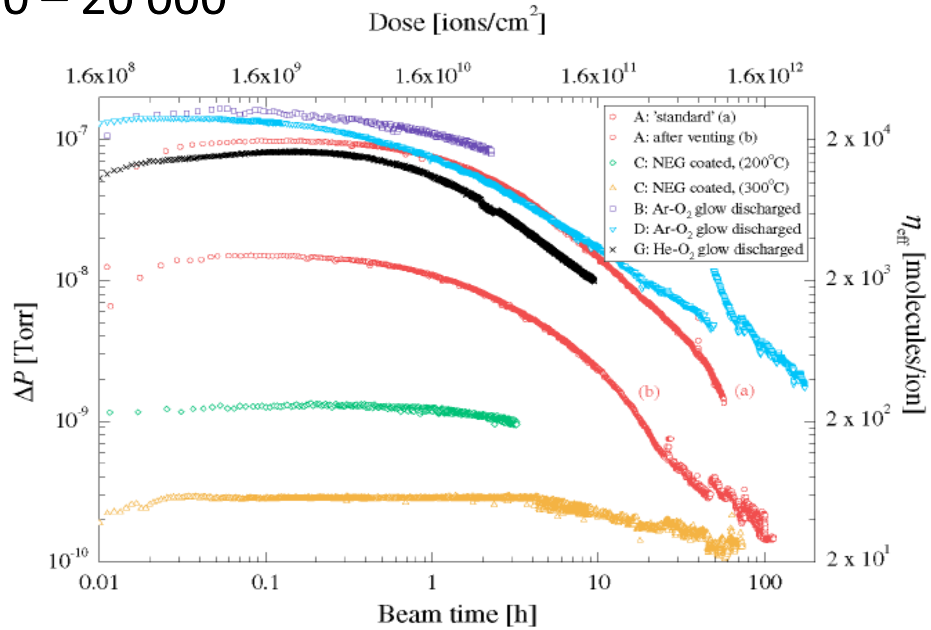
Pompe ionique triode

Ions à très haute énergie

- Des taux de desorption de 20 – 20 000

Pb^{53+}, 4. 2 MeV/u, 14 mrad

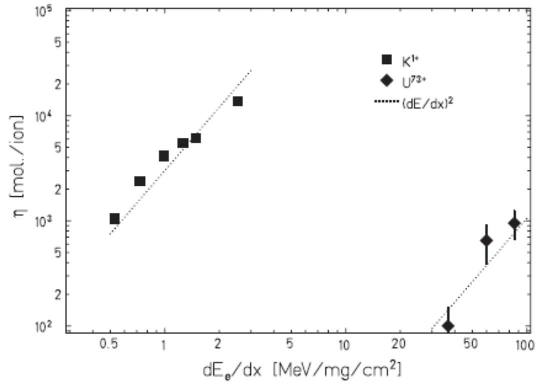
E. Mahner *et al.* , Phys. Rev. ST Accel. Beams 6, 013201 (2003)



- La désorption est déterminée par l' énergie donnée aux électrons (pouvoir d'arrêt électronique)

$$\eta_{ion} \propto \left(\frac{dE_e}{dx}\right)^2$$

L. Prost *et al.* , PRL 98, 064801 (2007)



- La désorption induite par les électrons est le mécanisme responsable

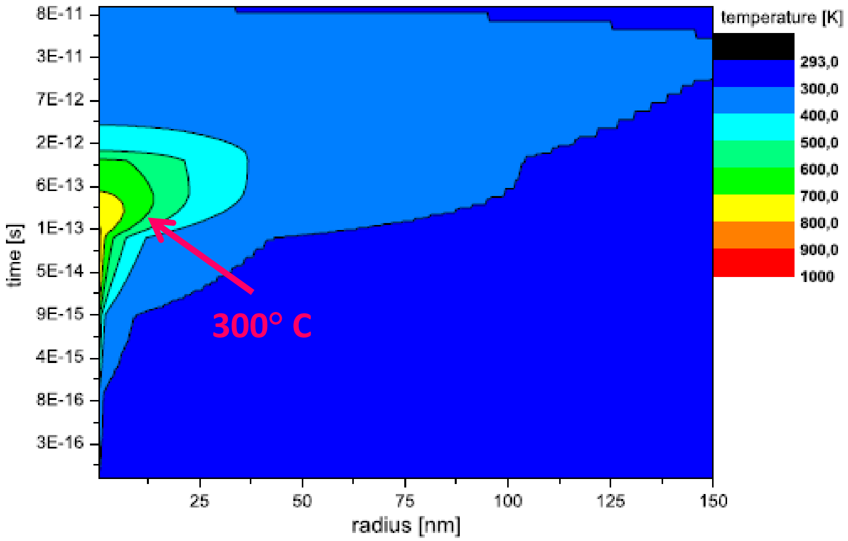
Mécanisme

- Effet de surface (sauf diffusion H_2) dû à une activation thermique
  - « Inelastic thermal spike model » : carte de température couplée au modèle de désorption thermique

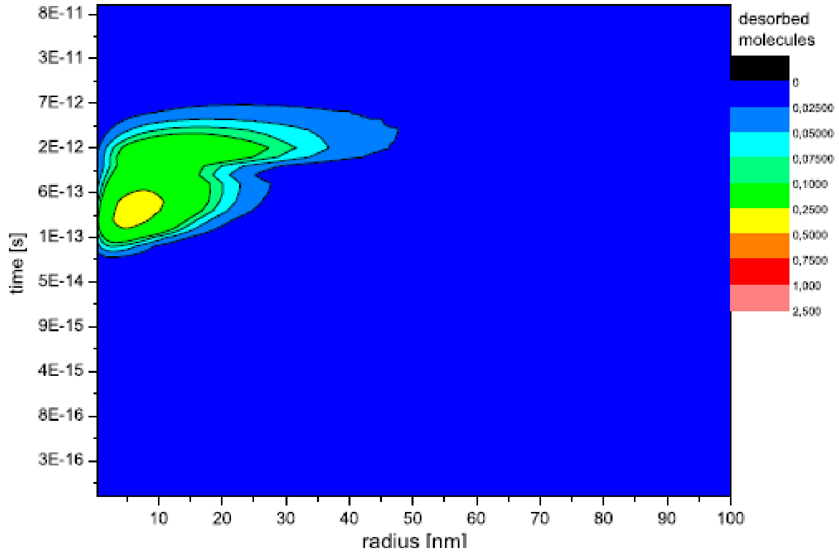
$$\eta = \int_0^{t_{max}} \int_0^{r_{max}} v_0(T(r,t)) \cdot \tilde{n}(r,t) \cdot \exp\left(-\frac{E_{des}}{k_B \cdot T(r,t)}\right) \cdot 2\pi \cdot r dr dt,$$

M. Bender *et al.* , NIM B 267 (2007) 885-890

Xe^{29+}, 1.4 MeV/u, Perpendiculaire



Temperature of atomic Cu subsystem after Xe impact



Desorbed particles per Xe per dt

$$\eta_{calculated} = 185$$

Remèdes

- Utilisation de revêtements NEG (LEIR, RHIC, GSI)

- Intercepter les ions « perdus » sur des collimateurs dédies :
  - LEIR : plaquage d'or de 30 µm sur de l'acier 316 LN, incidence perpendiculaire
  - GSI : plaquage d'or de 0.1 µm, incidence perpendiculaire. Absorbeur introduit dans une chambre secondaire. Revêtement NEG

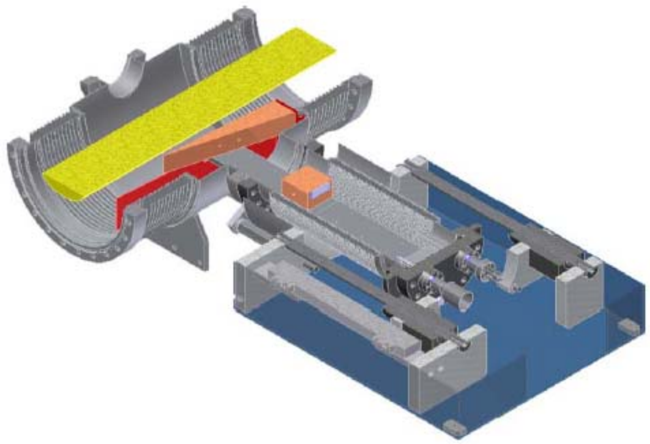
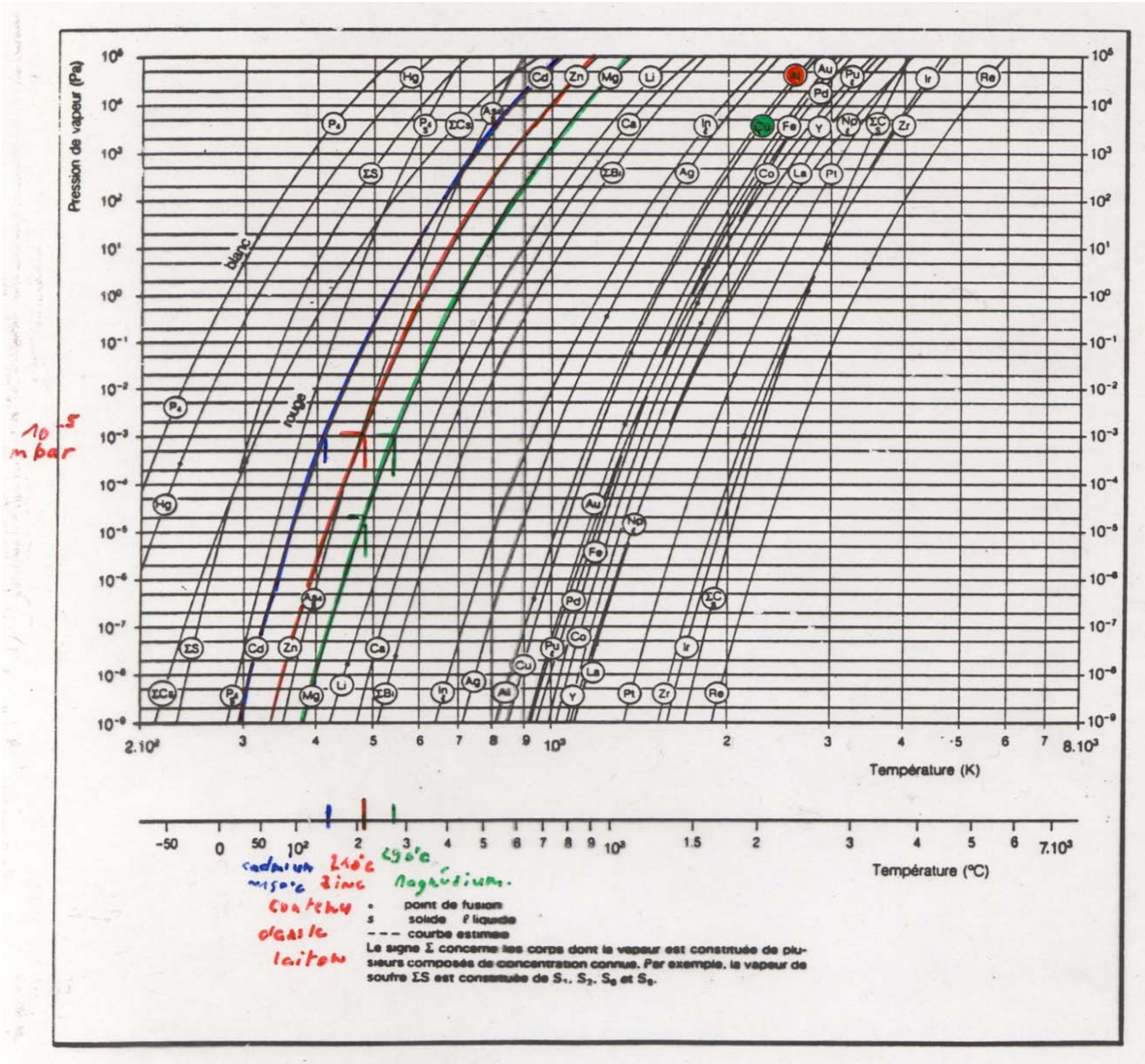


Figure 2: Horizontal cut through the installed SIS18 ion catcher prototype. Yellow: beam, red: secondary chamber, brown: beam absorbers.

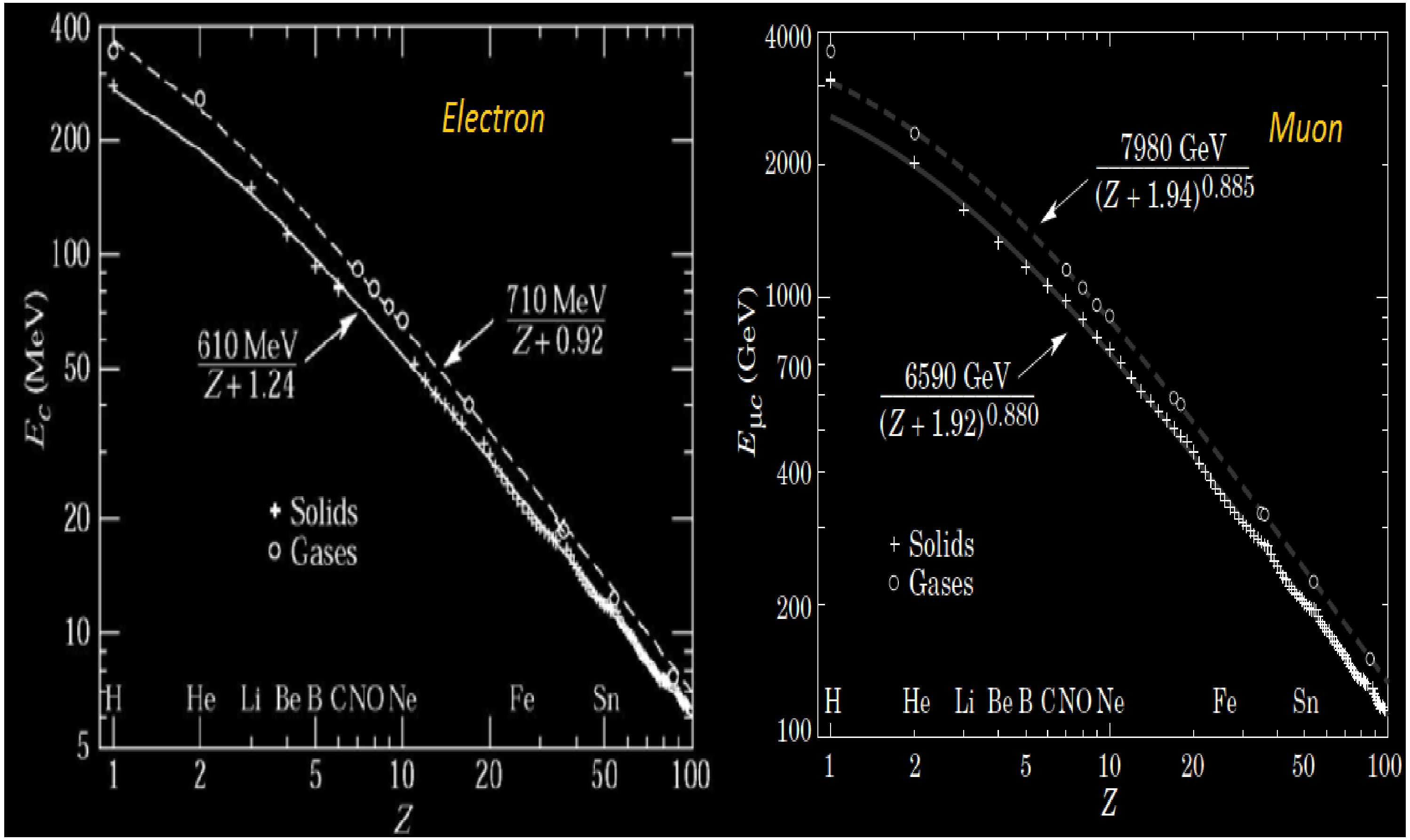
C. Omet *et. al.* EPAC 2008, Genoa, Italy

- Utiliser le conditionnement par le faisceau

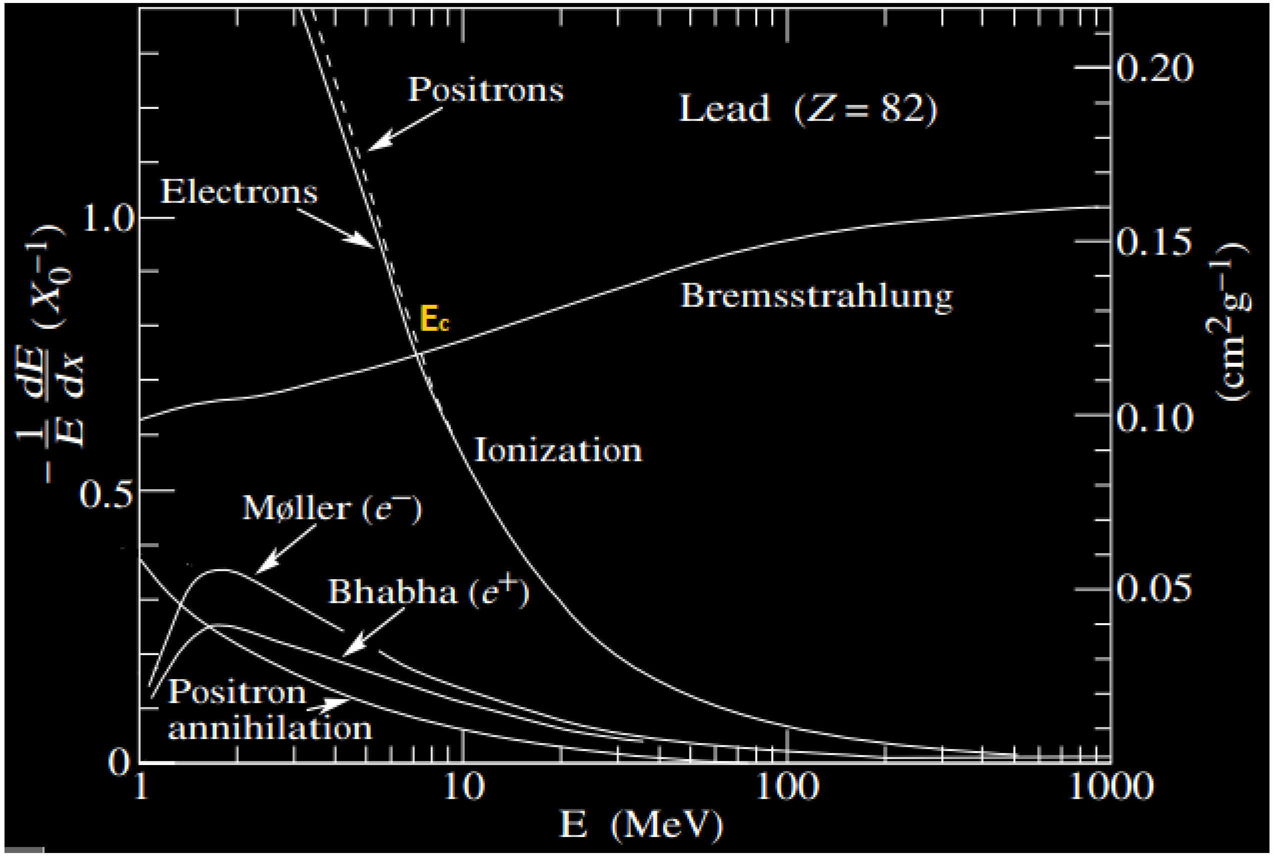
Vapor pressure



Energie critique ‘collision élastique/ émission radiative) en fonction de Z



Perte d’énergie des électrons dans du plomb par unité de radiation X0.
L’énergie critique est de 7,43 MeV.



Plomb 11,35 g/cm3 (20°C)